

# The 4D pixel challenge



Is it possible to build a tracker with concurrent excellent time and position resolution?

Can we provide from the same detector and readout chain:

**Timing resolution ~ 10 ps**  
**Space resolution ~ 10's of mm**

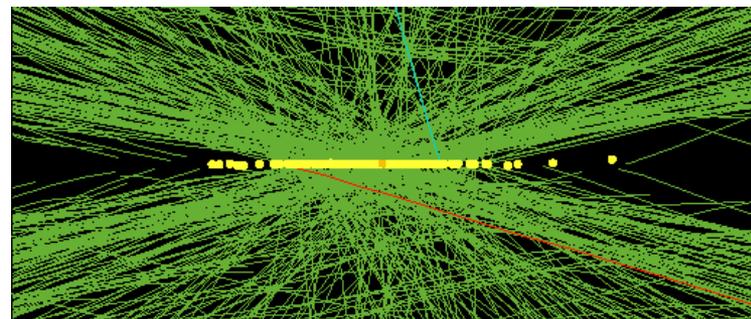
## Tracking in 4 Dimensions

The logo for the PIXEL 2016 project, with the word 'PIXEL' in large, multi-colored dot-matrix letters and '2016' below it in smaller, similar letters.

# Is timing really necessary?

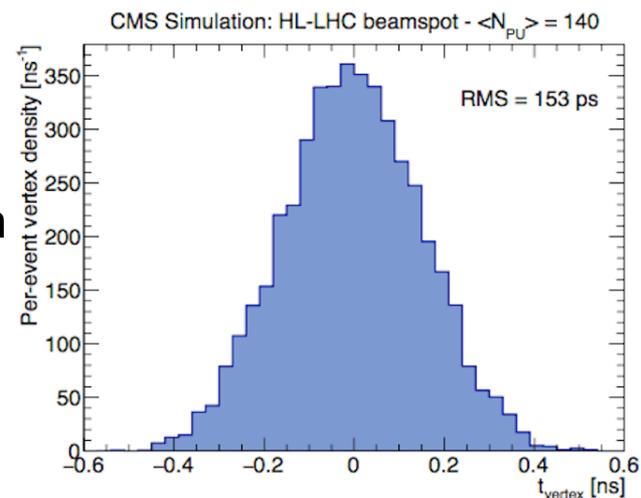
The research into 4D tracking is strongly motivated by the HL-LHC experimental conditions:

**150-200 events/bunch crossing**



According to CMS simulations:

- **Time RMS between vertexes: 153 ps**
- **Average distance between two vertexes: 500  $\mu\text{m}$**
- **Fraction of overlapping vertexes: 10-20%**
  - Of those events, a large fraction will have significant degradation of the quality of reconstruction



**At HL-LHC: Timing is equivalent to additional luminosity**

**In other experiments (NA62, PADME, Mu3e):**

**Timing is key to background rejection**

# The effect of timing information

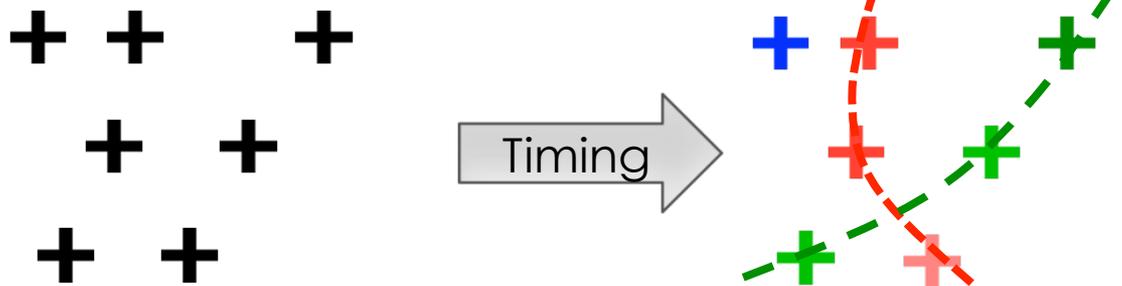
**The inclusion of track-timing in the event information has the capability of changing radically how we design experiments.**

**Timing can be available at different levels of the event reconstruction.**

- 1) Timing at each point along the track
- 2) Timing in the event reconstruction
- 3) Timing at the trigger level

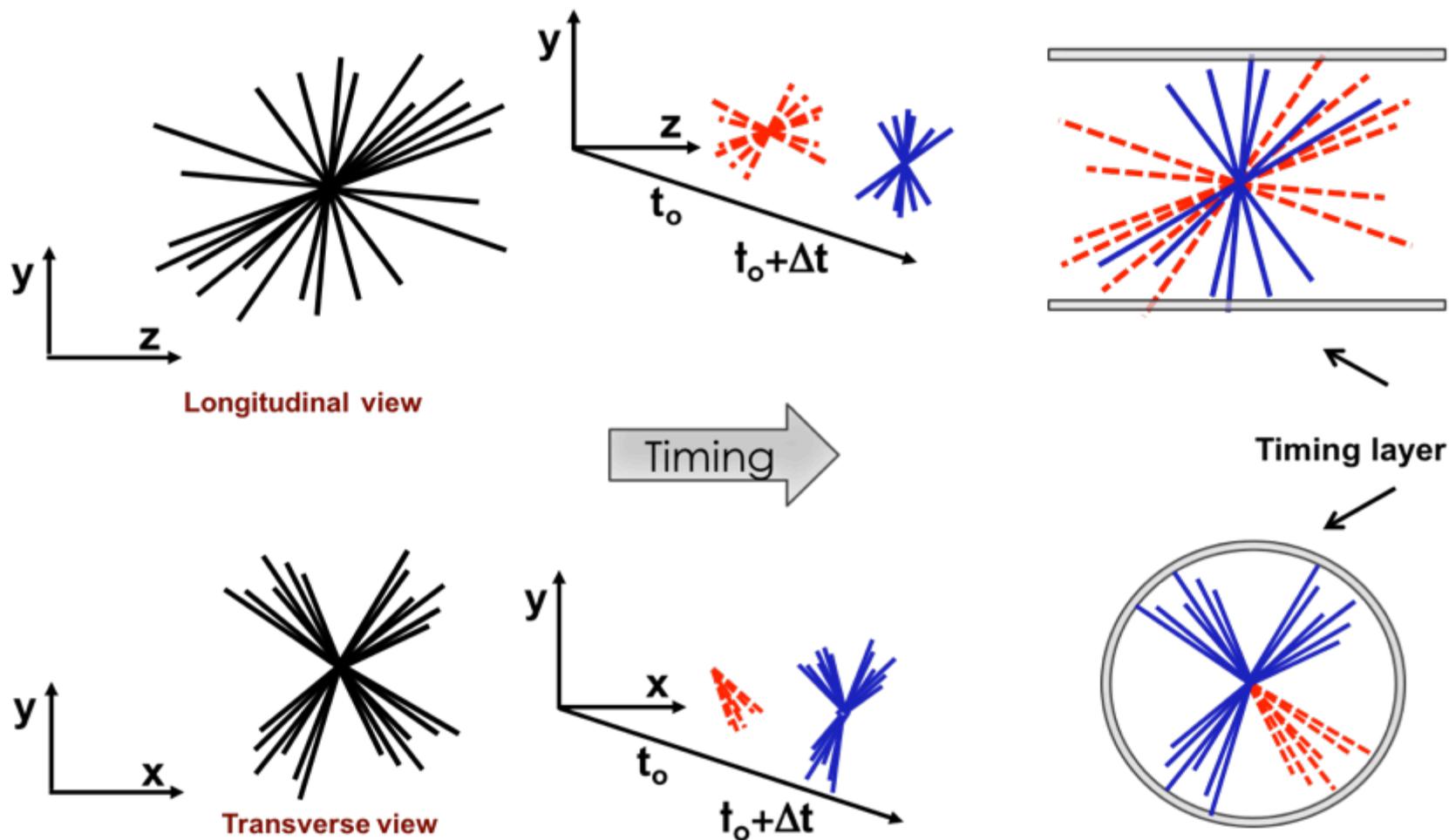
# Timing at each point along the track

- ➔ Massive simplification of pattern recognition, new tracking algorithms will be faster even in very dense environments
- ➔ Use only “time compatible points”



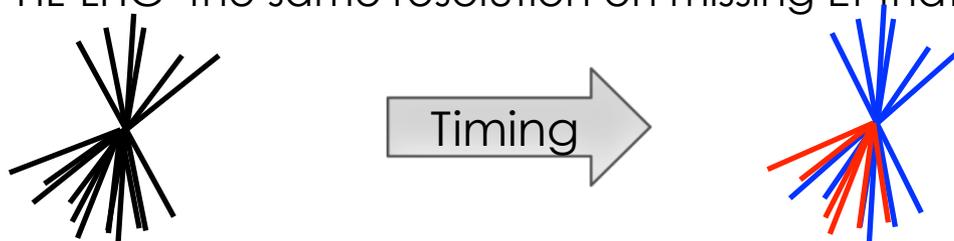
# Timing in the event reconstruction - I

Timing allows distinguishing overlapping events by means of an extra dimension.

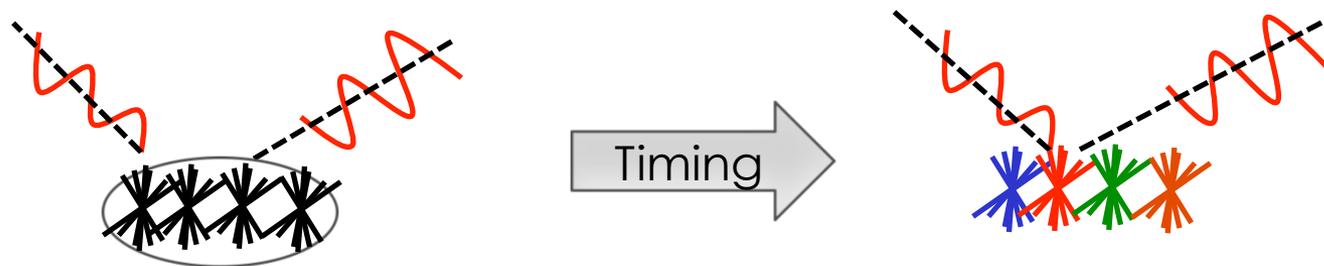


# Timing in the event reconstruction - II

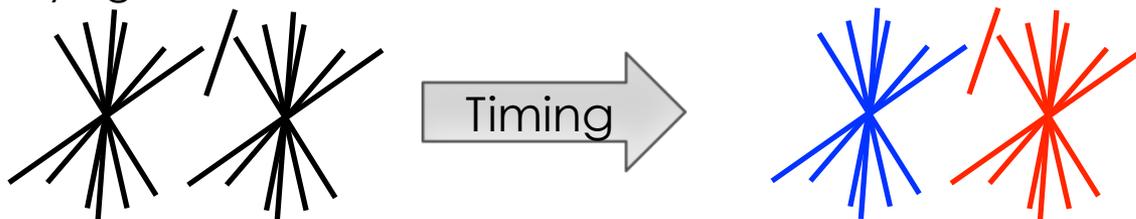
**Missing Et:** consider overlapping vertexes, one with missing Et: Timing allows obtaining at HL-LHC the same resolution on missing Et that we have now



**H  $\rightarrow$   $\gamma\gamma$ :** The timing of the  $\gamma\gamma$  allows to select an area (1 cm) where the vertex is located. The vertex timing allows to select the correct vertex within this area

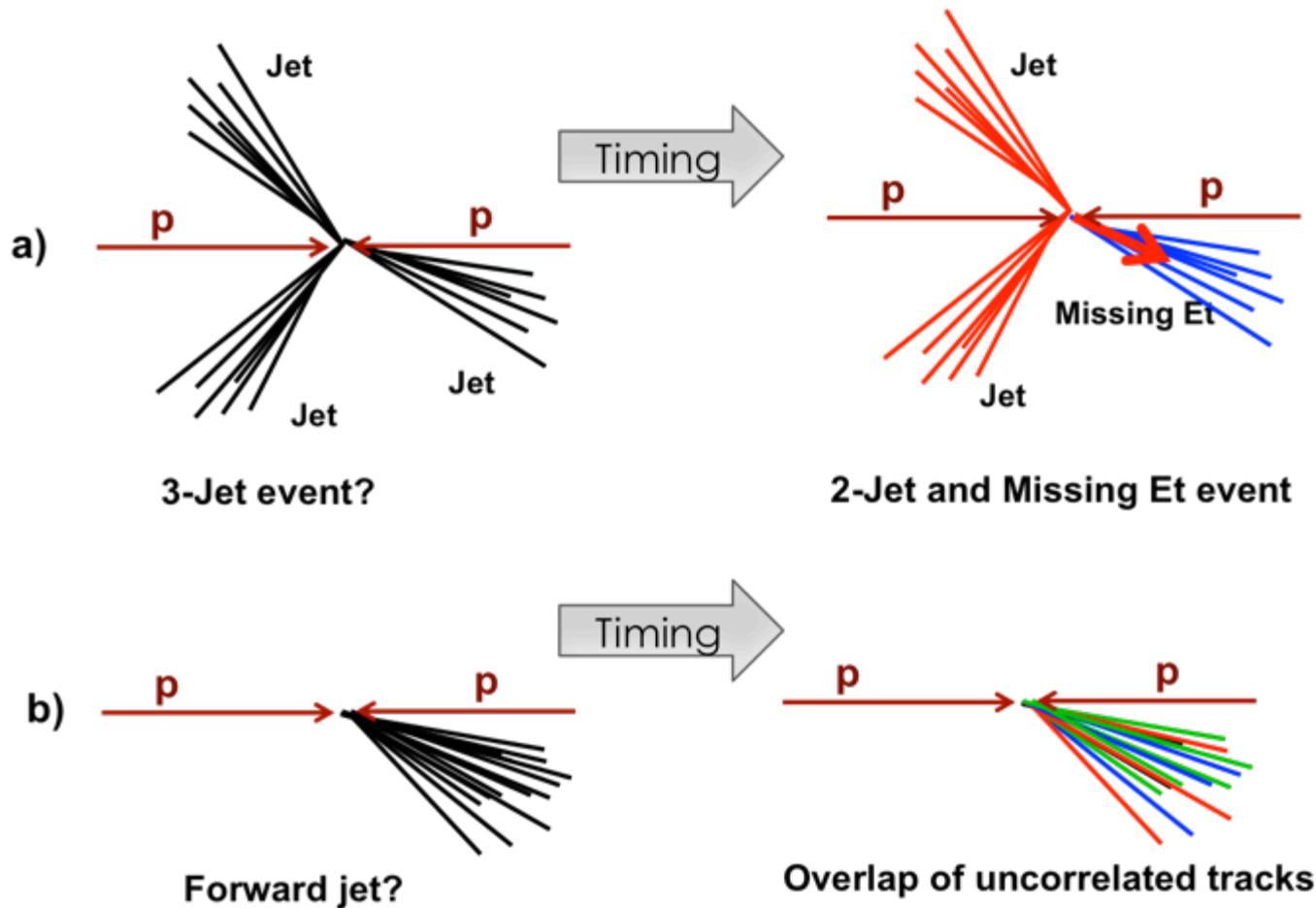


**Displaced vertexes:** The timing of the displaced track and that of each vertex allow identifying the correct vertex



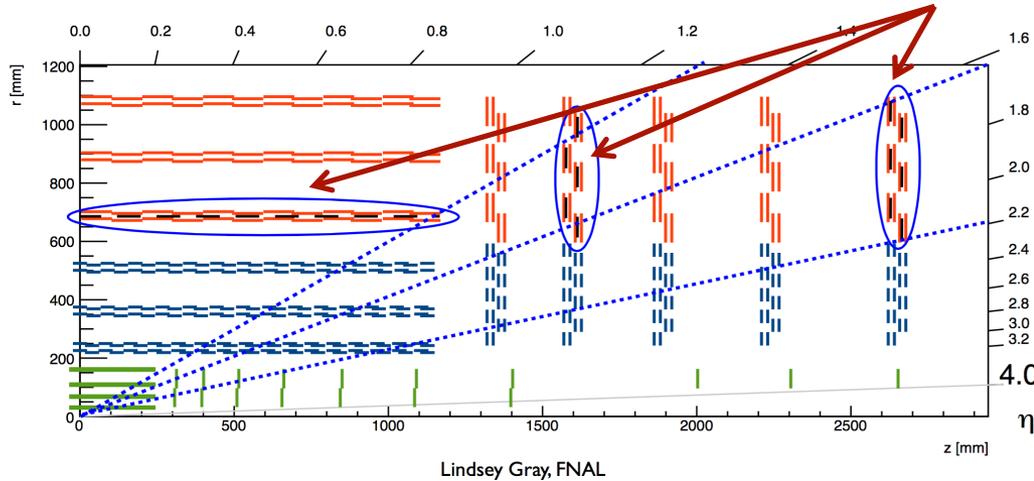
# The effect of timing information:

**Timing at the trigger decision:** it allows reducing the trigger rate, rejecting topologies that look similar, but they are actually different.

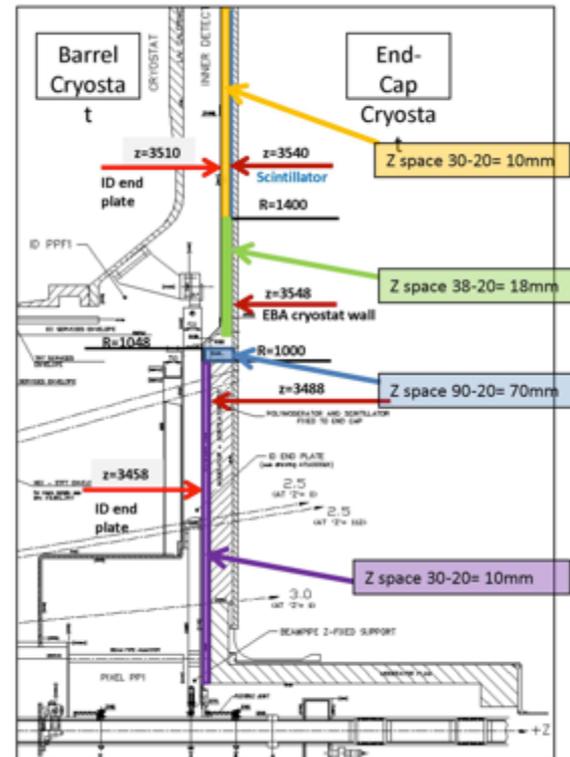


# Where do we place a track-timing detector?

Some (all?) layers in a silicon tracker can provide timing information



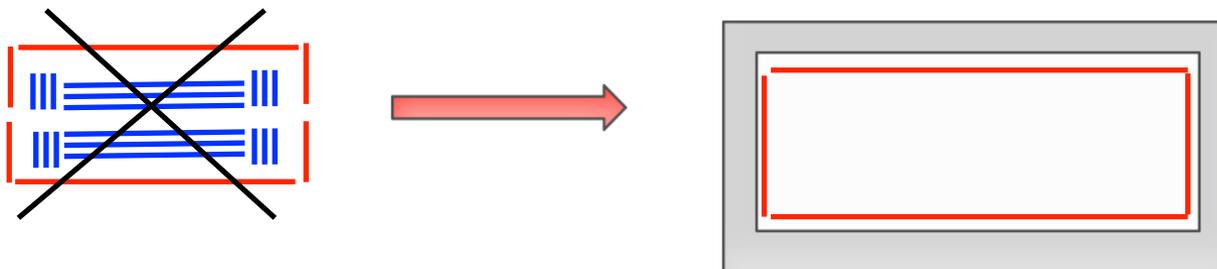
An additional detector can provide timing information, separated from the tracker



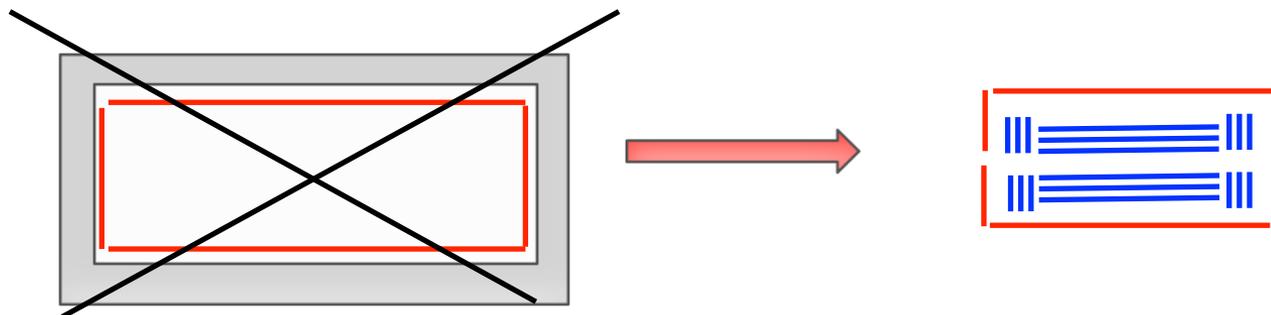
How do we build a 4D tracking system?

# Where do we stand?

**The tracking community** thinks it is a wonderful idea, clearly to be implemented **outside the tracker volume**, in front of the calorimeter



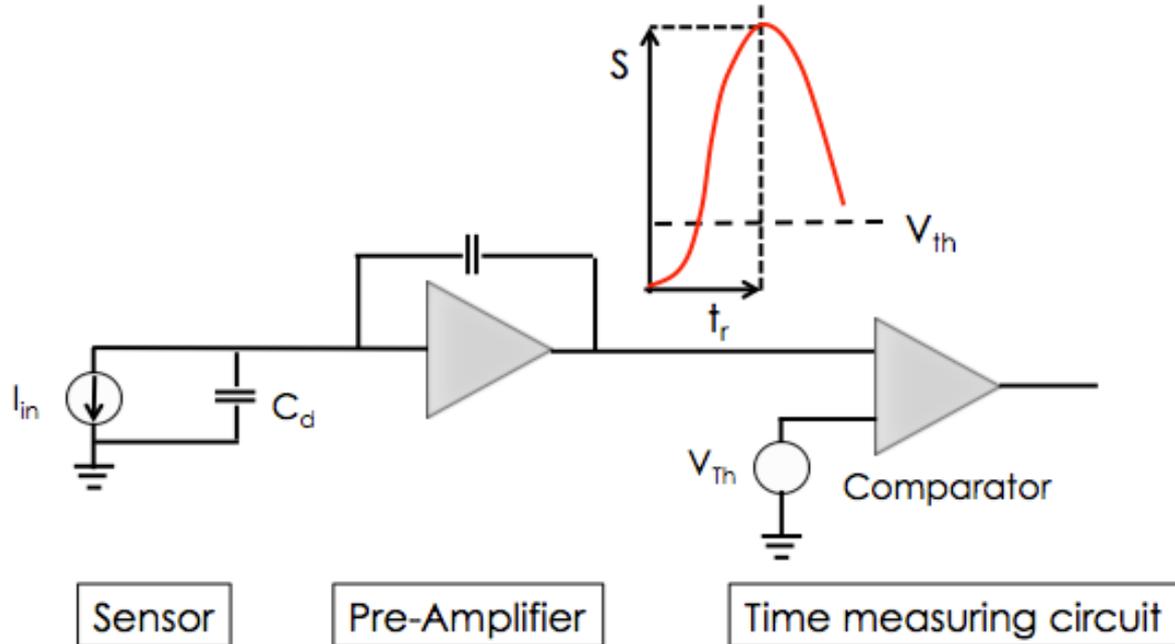
**The calorimeter community** thinks it is a wonderful idea, clearly to be implemented **far from the calorimeter**, in the tracker volume



We are now in contact with **the muon community....**

# A time-tagging detector

(a simplified view)



**Time is set when the signal crosses the comparator threshold**

The timing capabilities are determined by the characteristics of the signal at the output of the pre-Amplifier and by the TDC binning.

**Strong interplay between sensor and electronics**

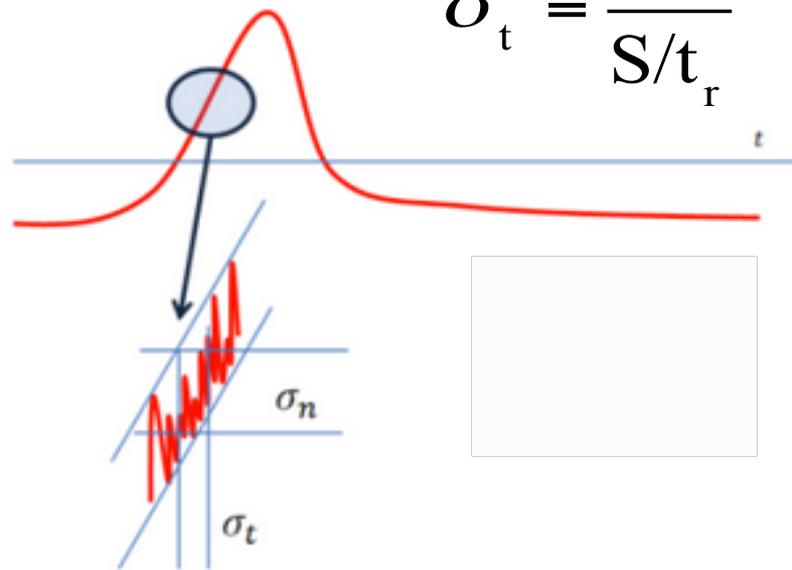
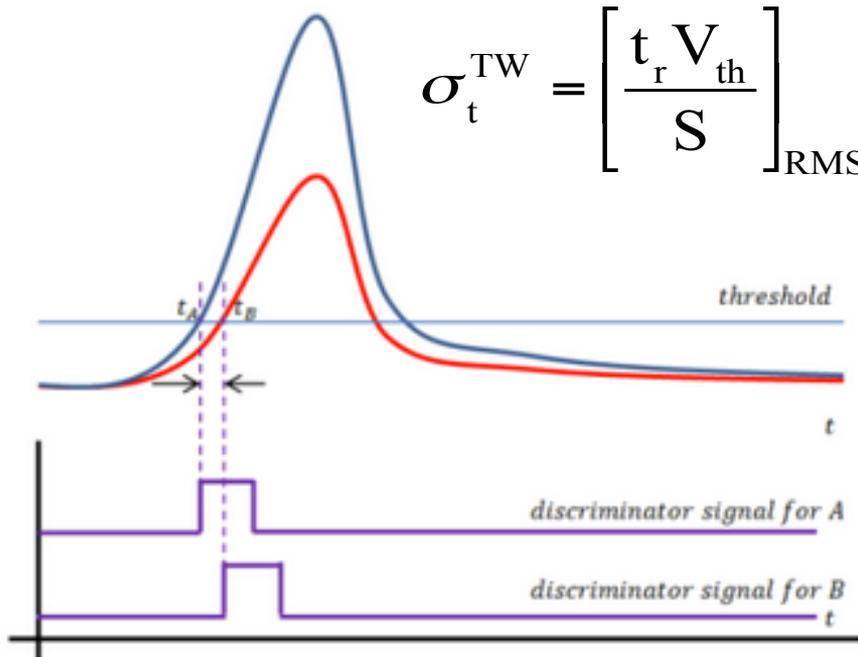
# 2 important effects: Time walk and Time jitter

**Time walk:** the voltage value  $V_{th}$  is reached at different times by signals of different amplitude

**Jitter:** the noise is summed to the signal, causing amplitude variations

$$\sigma_t^{TW} = \left[ \frac{t_r V_{th}}{S} \right]_{RMS}$$

$$\sigma_t^J = \frac{N}{S/t_r}$$



Due to the physics of signal formation

Mostly due to electronic noise

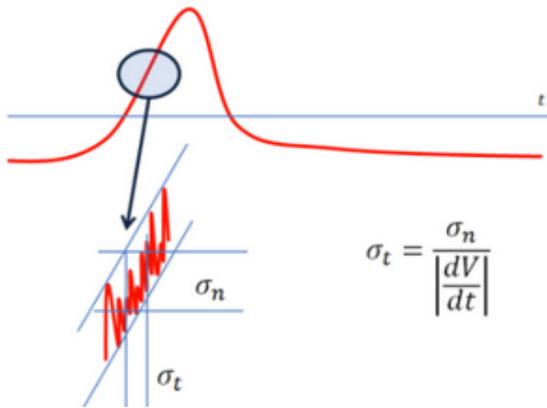
Time walk and jitter  $\sim N / (S/t_r) = N / (dV/dt)$

# Time resolution

$$\sigma_t = \left( \frac{N}{dV/dt} \right)^2 + (\text{Landau Shape})^2 + \text{TDC}$$

Usual "Jitter" term

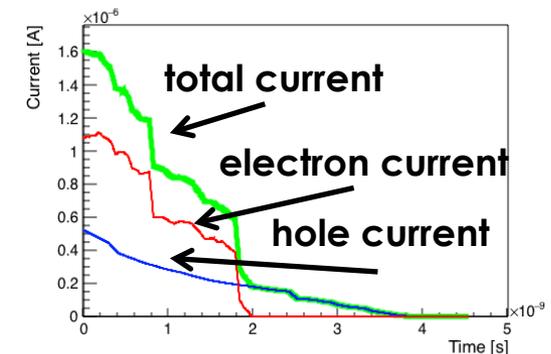
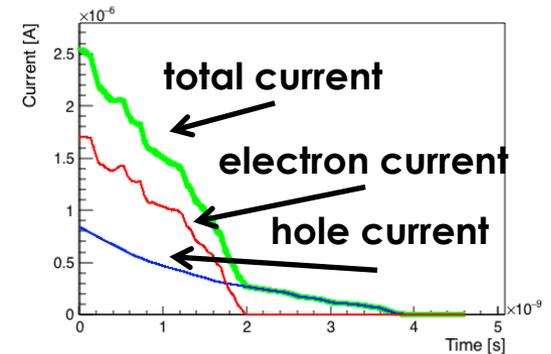
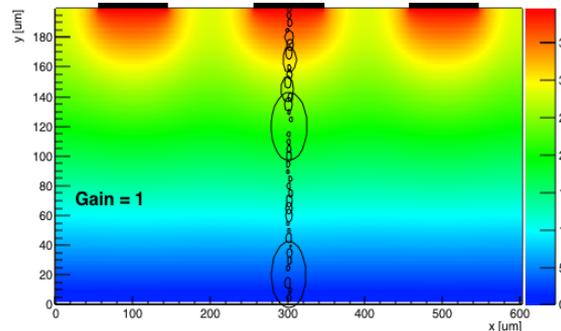
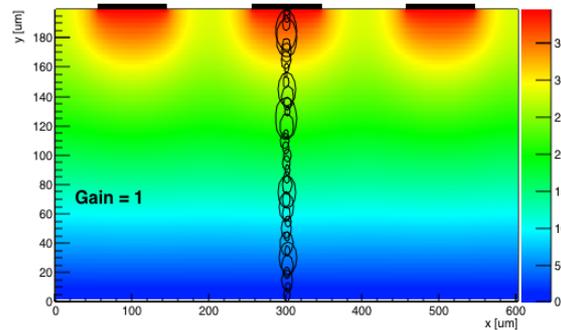
Here enters everything that is "Noise" and the steepness of the signal



$$\sigma_t = \frac{\sigma_n}{\left| \frac{dV}{dt} \right|}$$

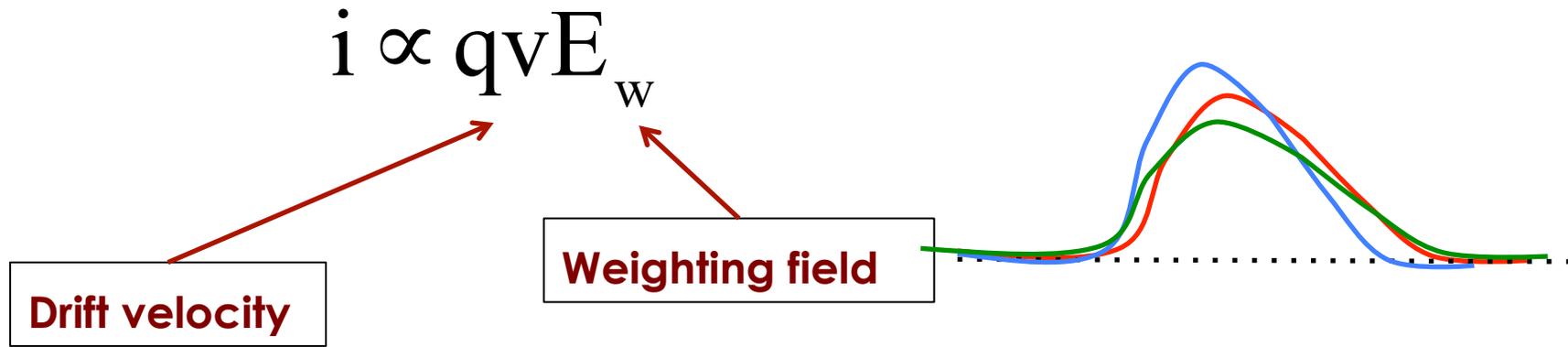
**Time walk:** time correction circuitry

**Shape variations:** non homogeneous energy deposition



# Not all geometries are possible

Signal shape is determined by Ramo's Theorem:

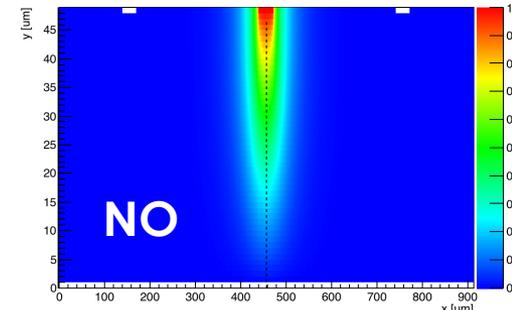
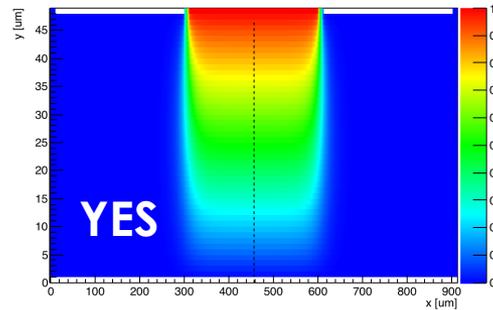


The key to good timing is the uniformity of signals:

**Drift velocity** and **Weighting field** need to be **as uniform as possible**

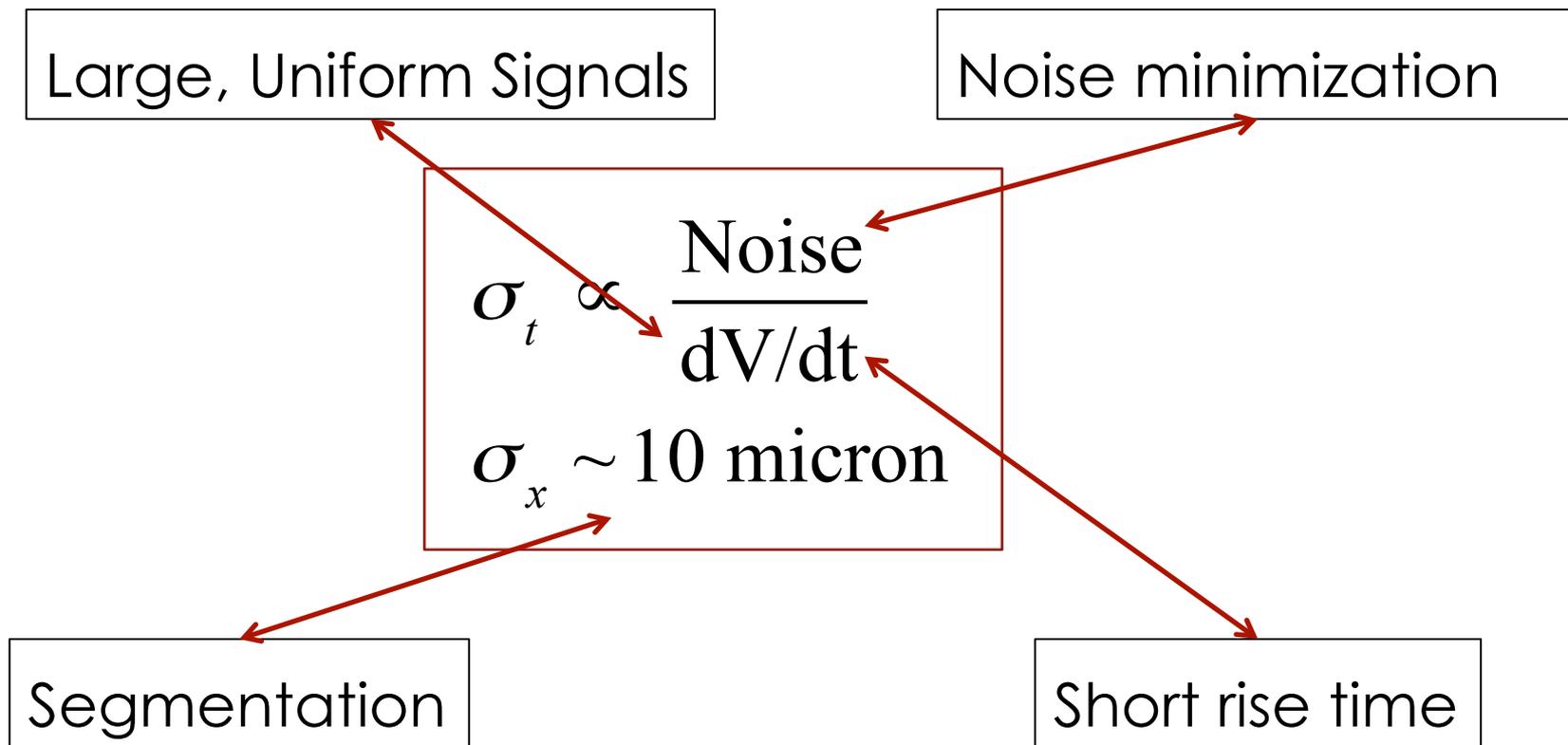
**Basic rule: parallel plate geometry: strip implant ~ strip pitch >> thickness**

Everything else does not work



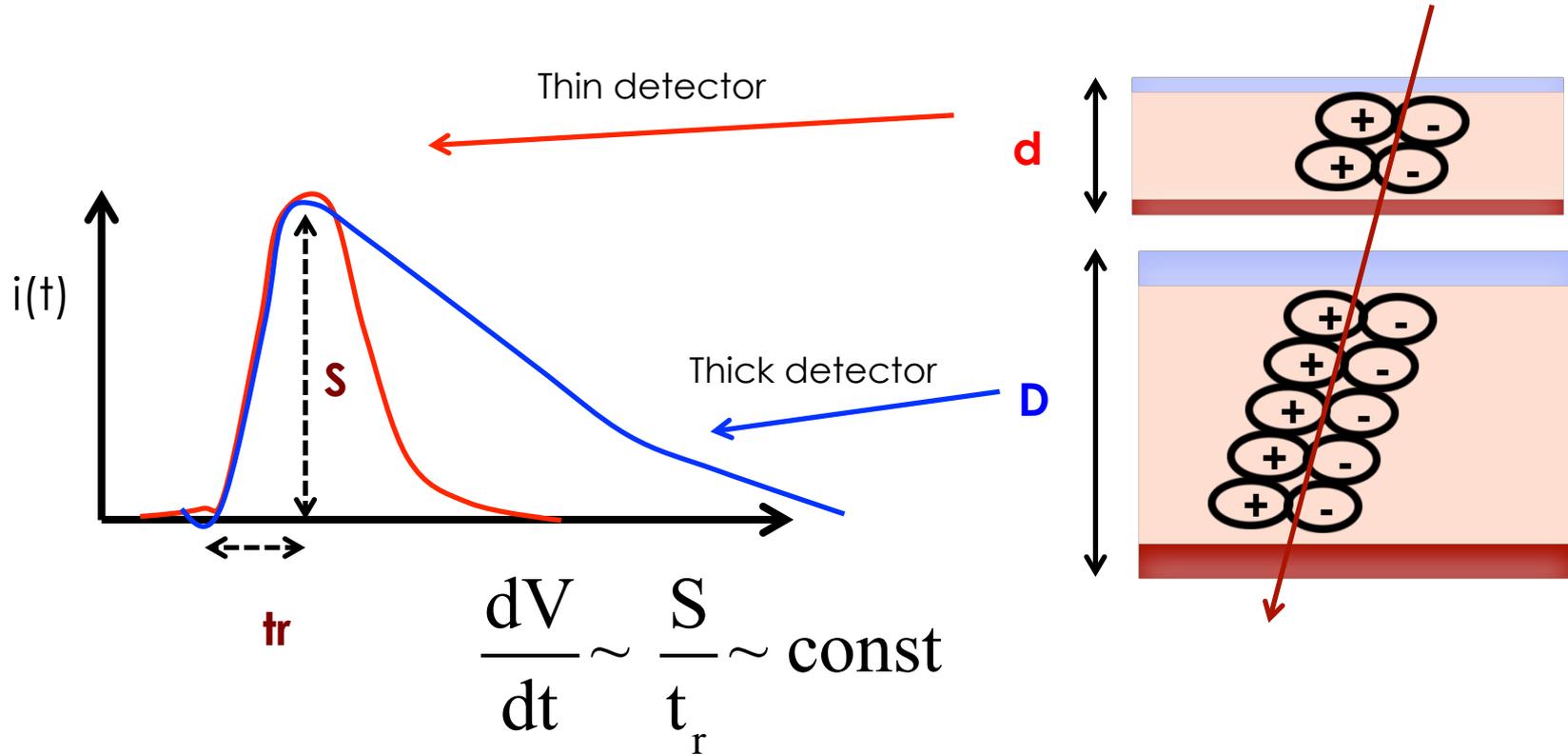
# 4-Dimensional High Precision Tracking

## The R&D program



# Thin vs Thick detectors

(Simplified model for pad detectors)

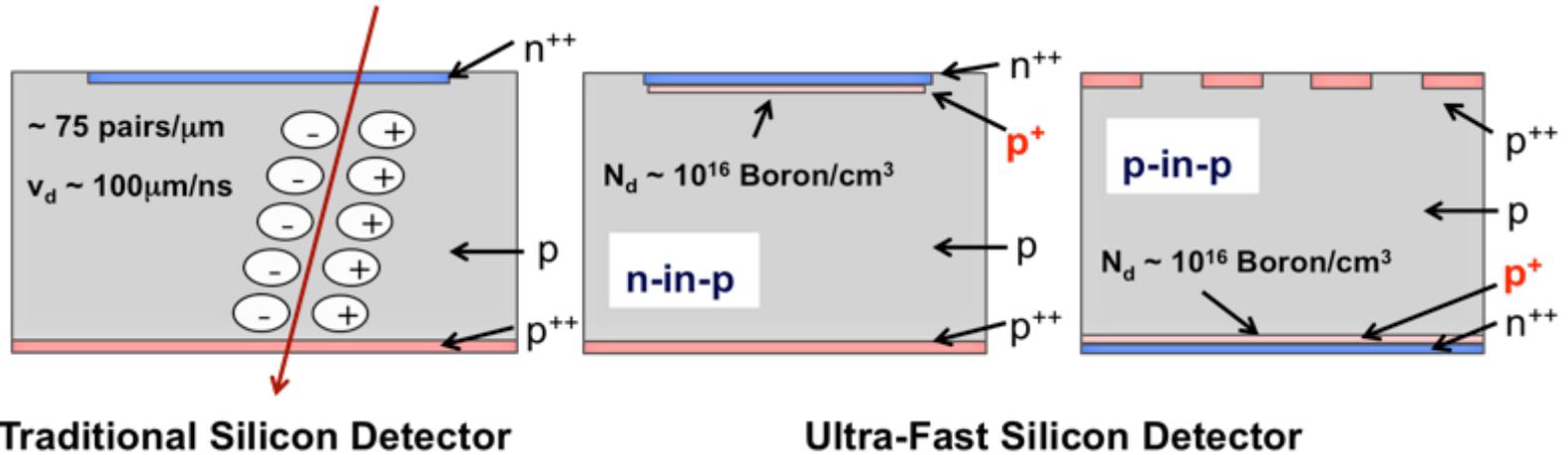


Thick detectors have longer signals, not higher signals

Best result : NA62, 150 ps on a 300 x 300 micron pixels

**How can we do better?**

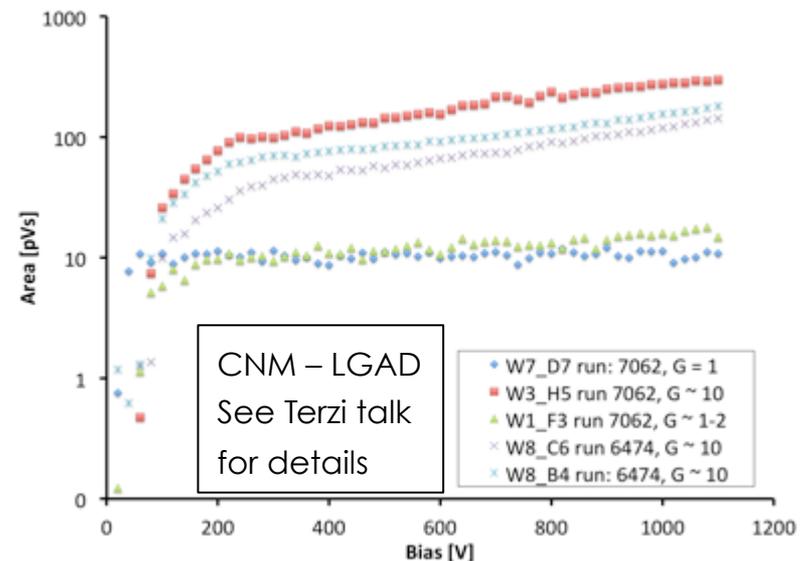
# LGAD - Ultra-Fast Silicon Detector



Adding a highly doped, thin layer of **p-implant** near the p-n junction creates a high electric field that accelerates the electrons enough to start multiplication. Same principle of APD, but with much lower gain.

**Gain changes very smoothly with bias voltage.**

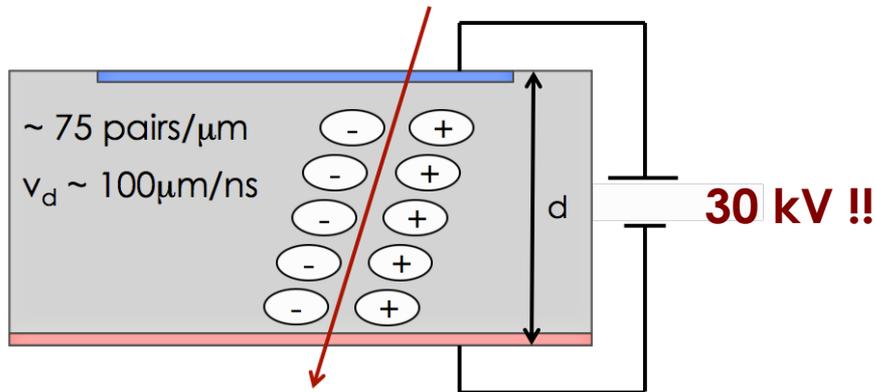
**Easy to set the value of gain requested.**



# How can we achieve $E \sim 300\text{kV/cm}$ ?

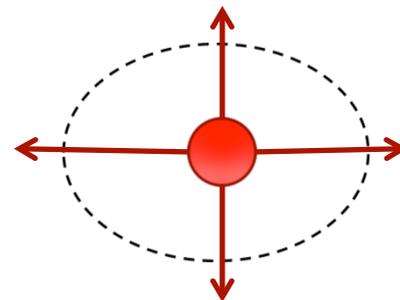
1) Use external bias: assuming a 300 micron silicon detector, we need  $V_{\text{bias}} = 30\text{ kV}$

**Not possible**



2) Use Gauss Theorem:

$$\sum q = 2\pi r * E$$



$$E = 300\text{ kV/cm} \rightarrow q \sim 10^{16} / \text{cm}^3$$

**Need to have  $10^{16}/\text{cm}^3$  charges !!**

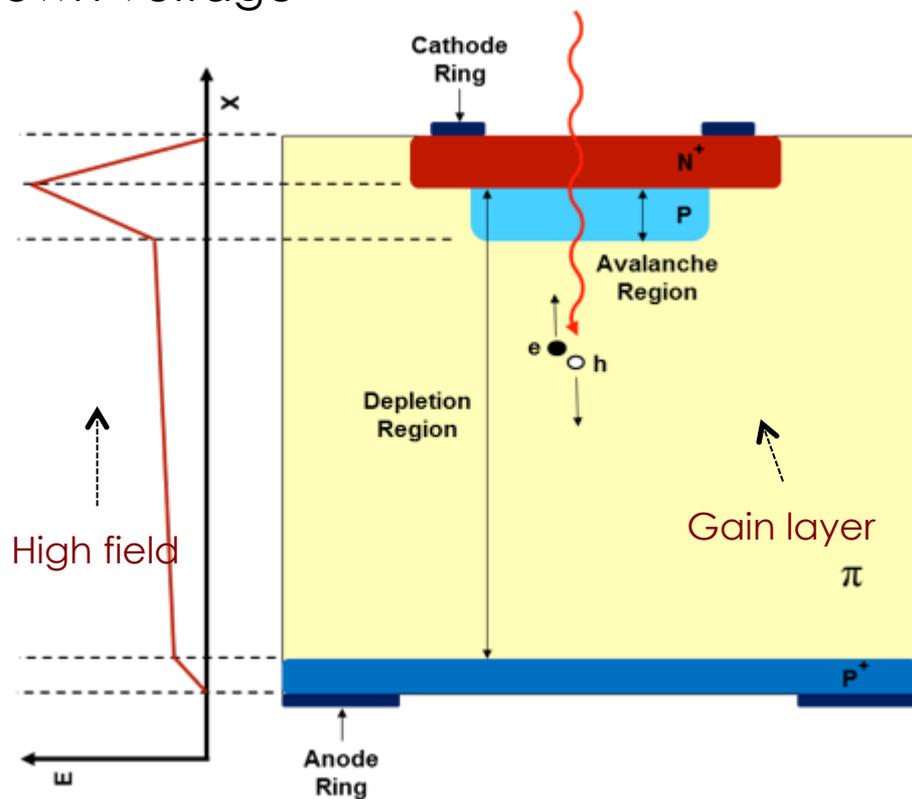
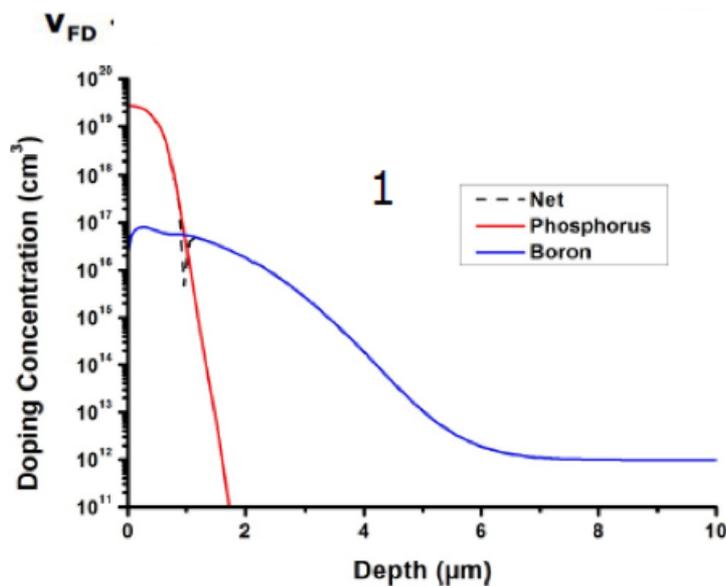
# Low Gain Avalanche Detectors (LGADs)

The LGAD sensors, as proposed and manufactured by CNM

(National Center for Micro-electronics, Barcelona):

**High field obtained by adding an extra doping layer**

$E \sim 300$  kV/cm, closed to breakdown voltage

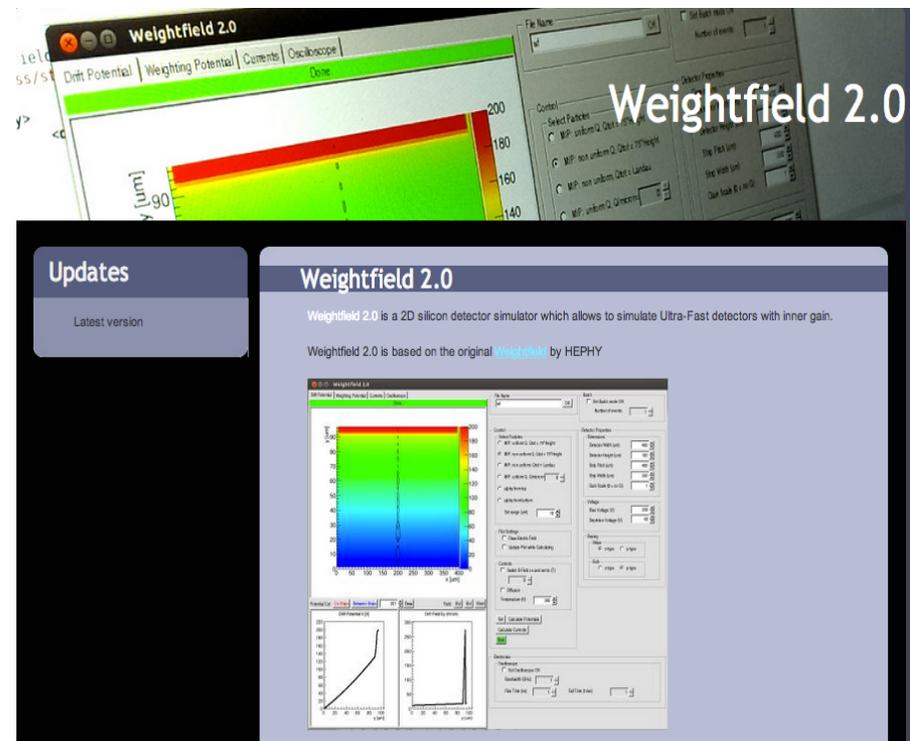


We developed a full sensor simulation to optimize the sensor design

WeightField2, F. Cenna, N. Cartiglia 9<sup>th</sup> Trento workshop, Genova 2014  
 Available at <http://personalpages.to.infn.it/~cartigli/weightfield2>

## It includes:

- Custom Geometry
- Calculation of drift field and weighting field
- Currents signal via Ramo's Theorem
- Gain
- Diffusion
- Temperature effect
- Non-uniform deposition
- Electronics



**For each event, it produces a file with the current output that can be used as input in the simulation of the electronic response.**

# WeightField2: a program to simulate silicon detectors

Drift Potential | Weighting Potential | Currents and Oscilloscope | Electronics
Weightfield 2.6

Done.

Plotting at: On Strips Between Strips 465 Draw

Drift Potential V [V]

Drift Field E (kV/cm)

Control

Precision (1=best, 10=fastest): 10

Sampling (GigaSample): 100

File Name

ON wf

Batch

ON # of events: 1

Select Particles

MIP: uniform Q, Qtot = 75\*Height

MIP: non uniform Q, Qtot = 75\*Height

MIP: non uniform, Qtot = Landau

MIP: uniform Q, Q/micron = 75

alpha from top (E = 5 MeV)

alpha from bottom (E = 5 MeV)

Set range (Max = 30 um): 10

Plot Settings

Draw Electric Field

No 1D Plots  No 1D & 2D

Currents

Switch B-Field on and set to (T): 0

Diffusion

Temperature (K): 300

Set
Calculate Potentials

Calculate Currents
Stop
Exit

Detector Properties

Type

Si  Diamond  Free

Strips

n-type  p-type

Bulk

n-type  p-type

Dimensions

# of strips (1,3,5,...): 3

Detector Height (um): 285

Strip Pitch (um): 300

Strip Width (um): 290

Gain Scale (1 = no G): 1

Force Fixed Gain:  ON

h/e Gain ratio: 0

Gain layer recess (um): 0

Voltage

Bias Voltage (V): 800

Depletion Voltage (V): 40

Electronics

ON

Detector Cap (pF): 1

Oscilloscope BW (GHz): 2.5

Shaper T<sub>r</sub> - T<sub>f</sub> (ns): 3.5 8

Shaper Trans Imp. (mV/IQ): 4

Shaper Noise & V<sub>th</sub> (mV): 1 10

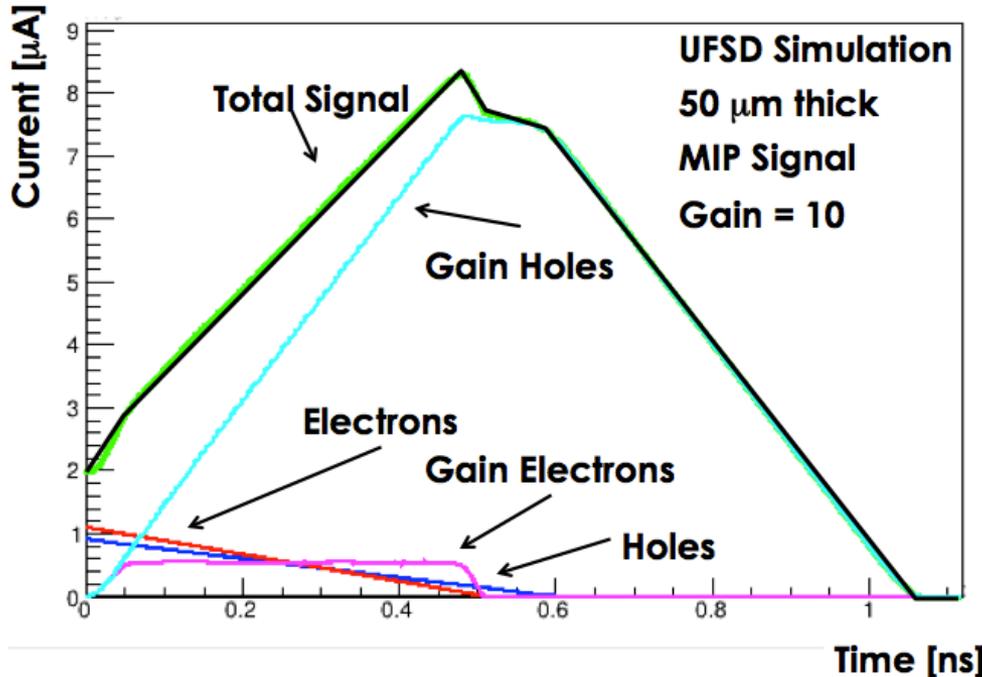
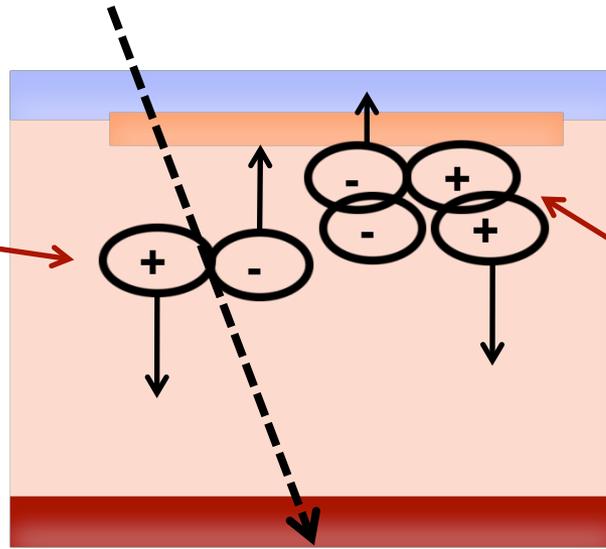
PreAmp input Imp. (Ohm): 50

# How gain shapes the signal

**Gain electron:**  
absorbed immediately

**Gain holes:**  
long drift home

Initial electron, holes

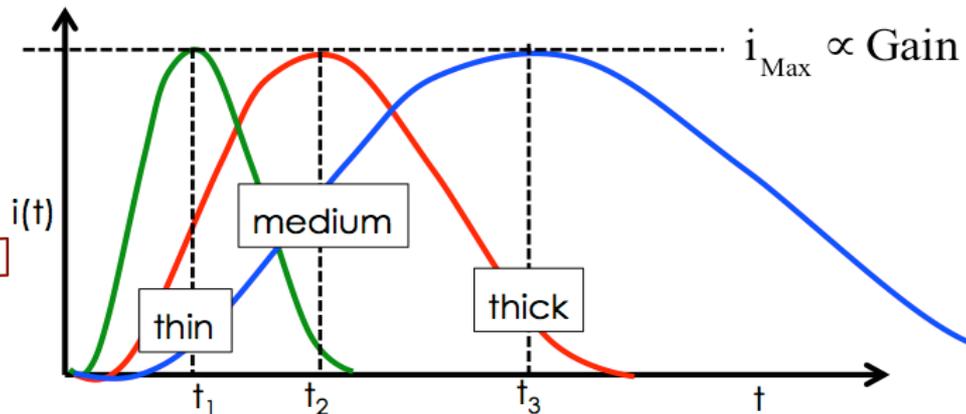


Electrons multiply and produce additional electrons and holes.

- **Gain electrons have almost no effect**
- **Gain holes dominate the signal**

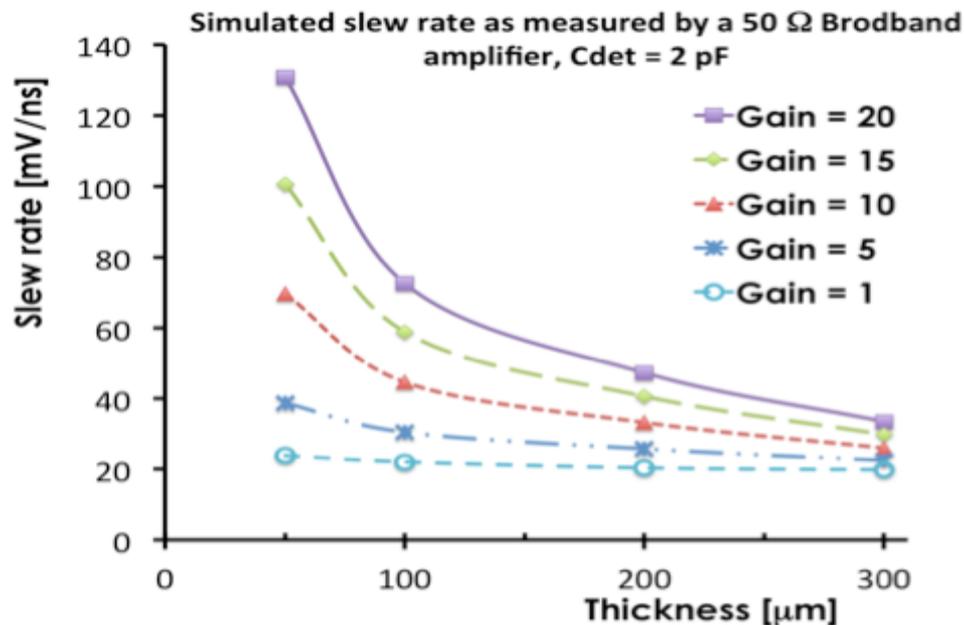
➔ **No holes multiplications**

# Gain and slew rate vs thickness



**For a fixed gain:**

- amplitude = constant
- rise time  $\sim 1/\text{thickness}$



**The slew rate:**

- Increases with gain
- Increases  $\sim 1/\text{thickness}$

**→ Go thin!!**

**Significant improvements in time resolution require thin detectors**

# Ultra Fast Silicon Detectors

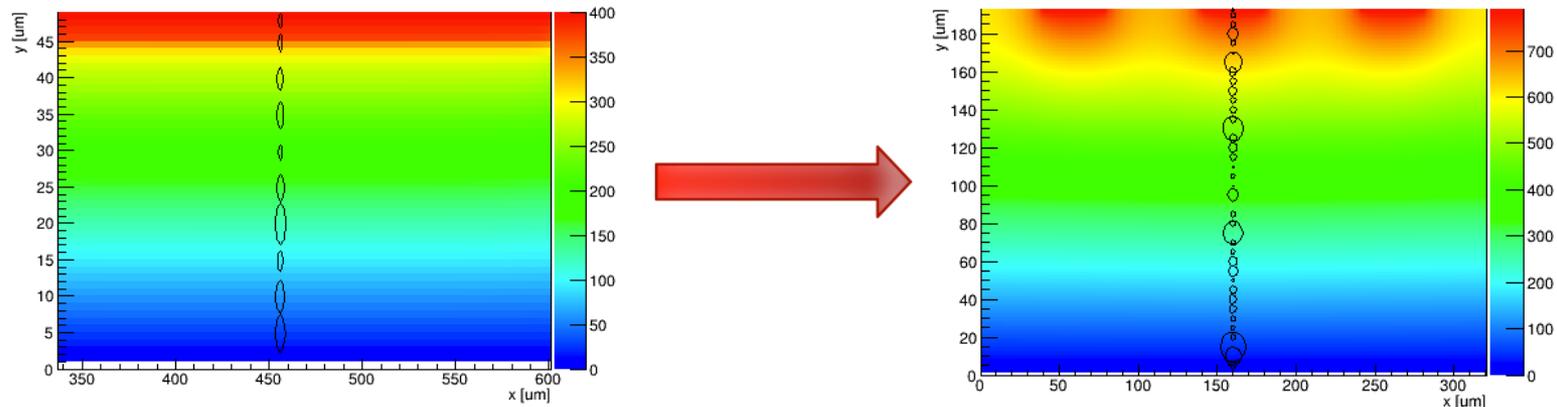
**UFSD are LGAD detectors optimized to achieve the best possible time resolution**

## **Specifically:**

1. Thin to maximize the slew rate ( $dV/dt$ )
2. Parallel plate – like geometries (pixels..) for most uniform weighting field
3. High electric field to maximize the drift velocity
4. Highest possible resistivity to have uniform E field
5. Small size to keep the capacitance low
6. Small volumes to keep the leakage current low (shot noise)

# Merging timing with position resolution

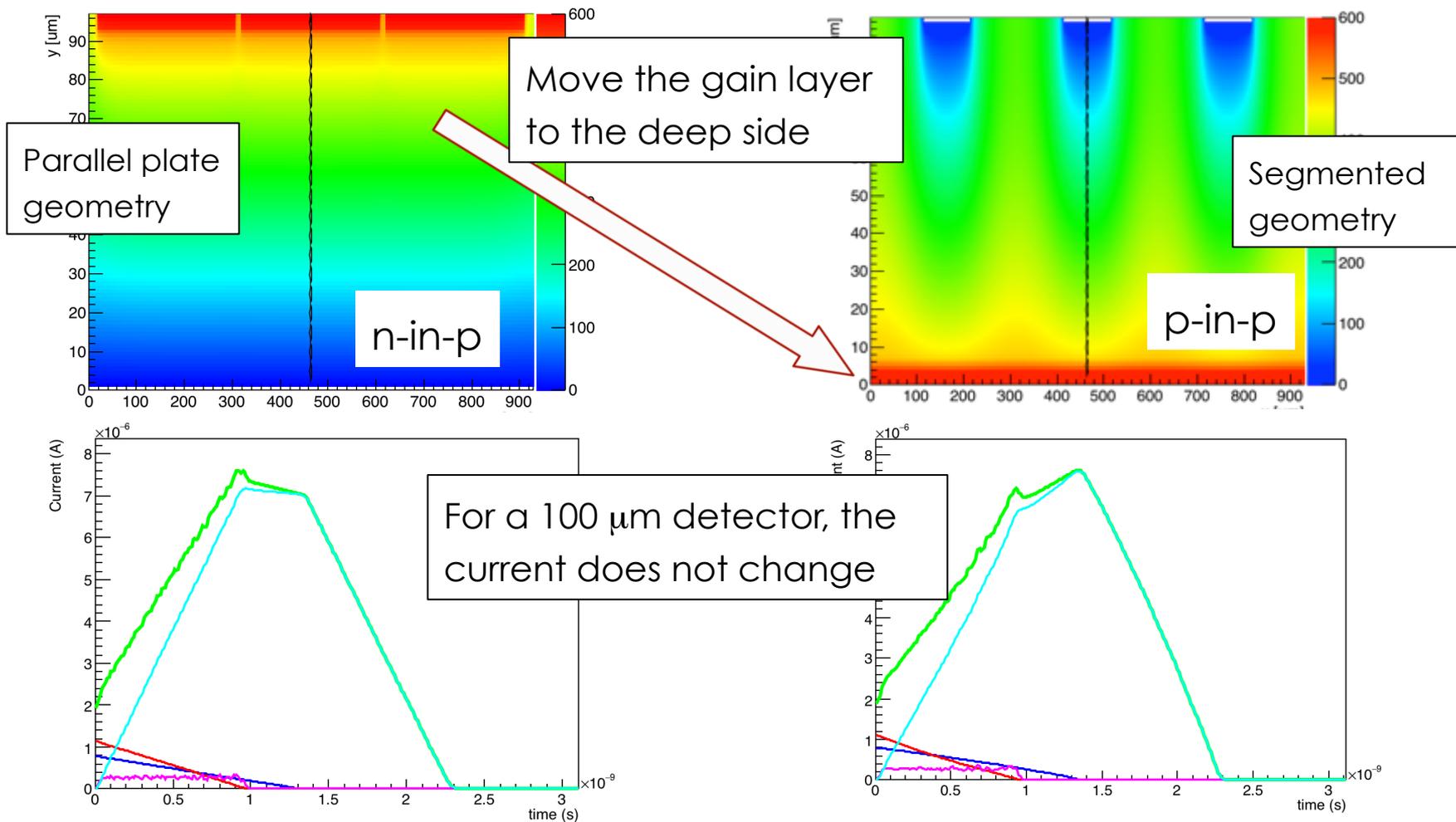
Electrode segmentation makes the E field very non uniform, and therefore ruins the timing properties of the sensor



We need to find a geometry that has very uniform E field and gain, while allowing electrode segmentation.

# 1) Segmentation: buried junction

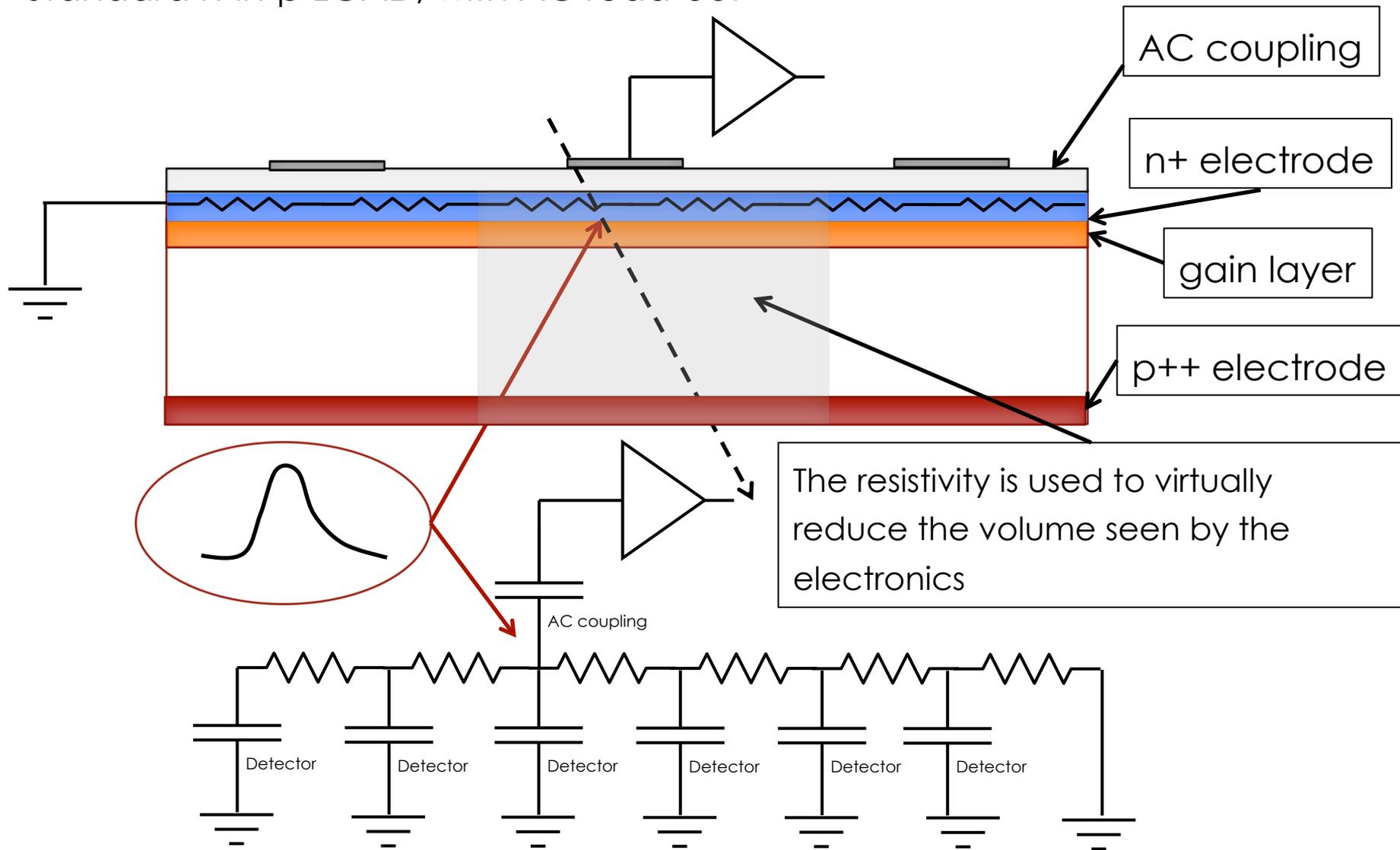
Separate the multiplication side from the segmentation side



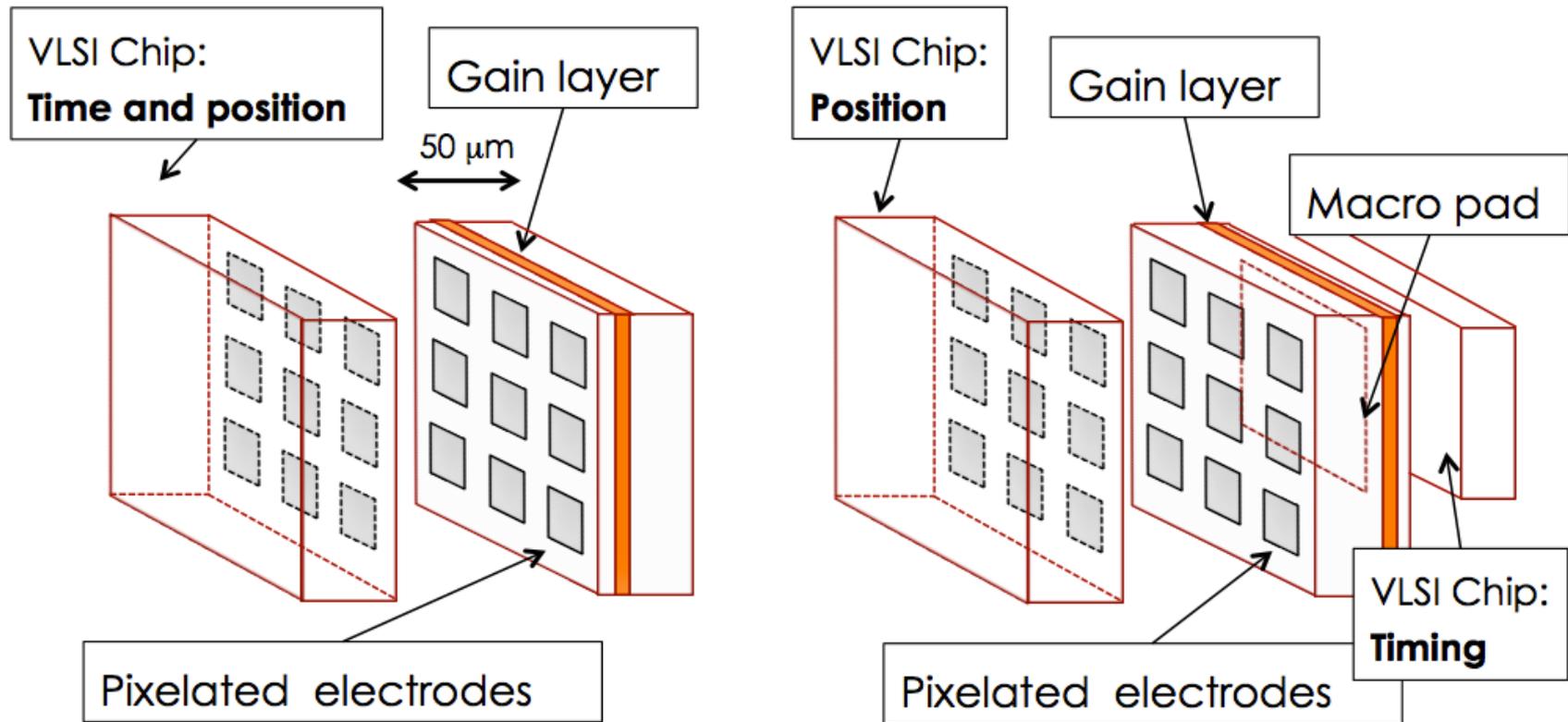
Moving the junction on the deep side allows having a very uniform multiplication, regardless of the electrode segmentation

## 2) Segmentation: AC coupling

Standard n-in-p LGAD, with AC read-out



### 3) Segmentation: splitting gain and position measurements

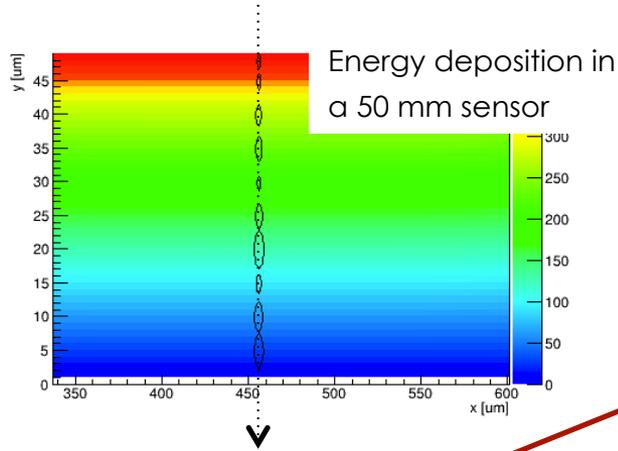


**The real solution: monolithic**

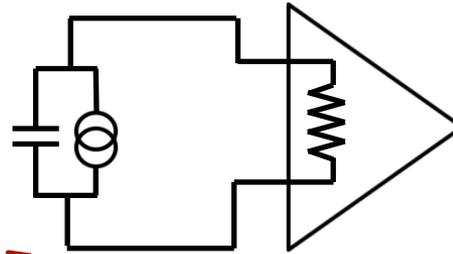
> 10 years

This is the correct approach, however it will take time.

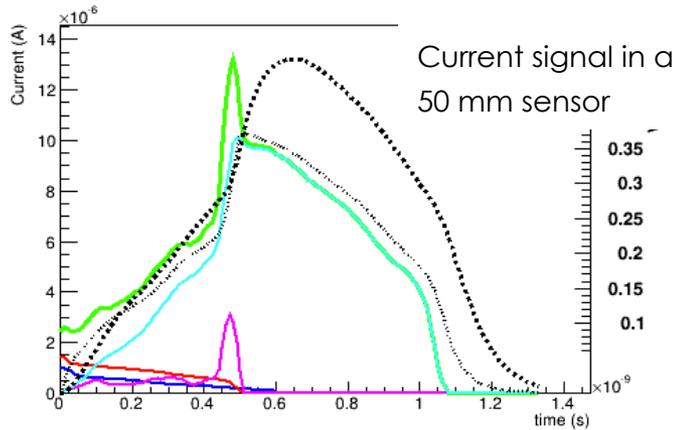
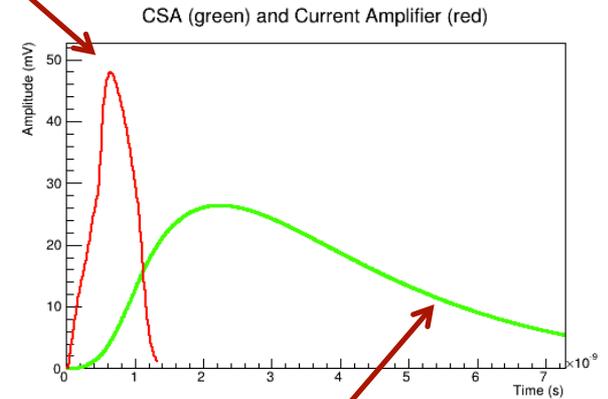
# What is the best pre-amp choice?



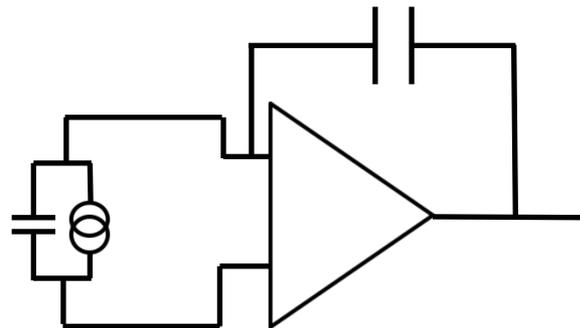
## Current Amplifier



- Fast slew rate
- Higher noise
- Sensitive to Landau bumps
- More power

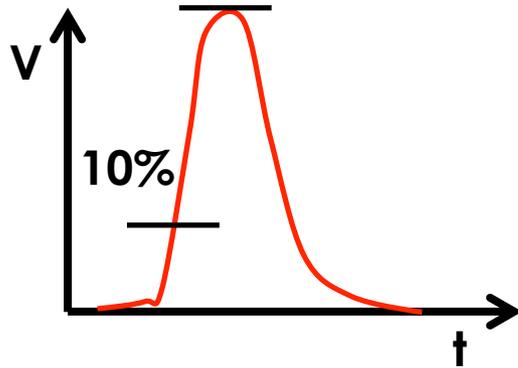


## Integrating Amplifier



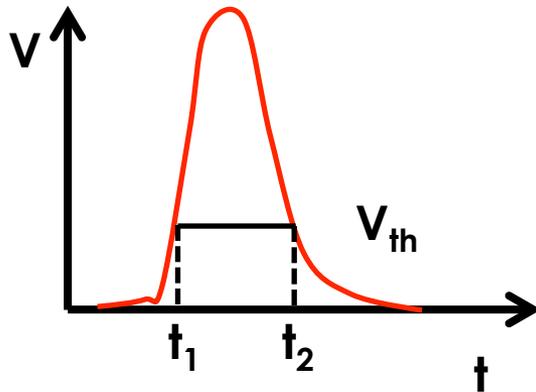
- Slower slew rate
- Lower noise
- Signal smoothing
- Less power

# What is the best “time measuring” circuit?



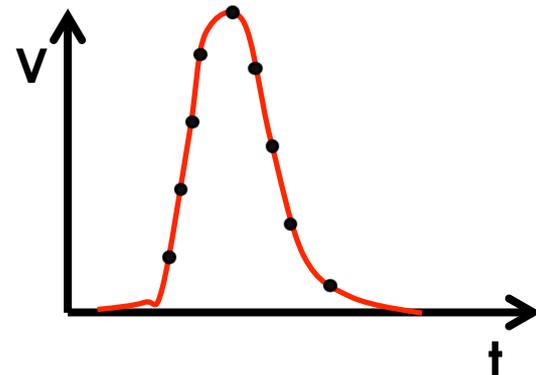
## Constant Fraction Discriminator

The time is set when a fixed fraction of the amplitude is reached



## Time over Threshold

The amount of time over the threshold is used to correct for time walk



## Multiple sampling

Most accurate method, needs a lot of computing power.

Possibly too complicated for large systems

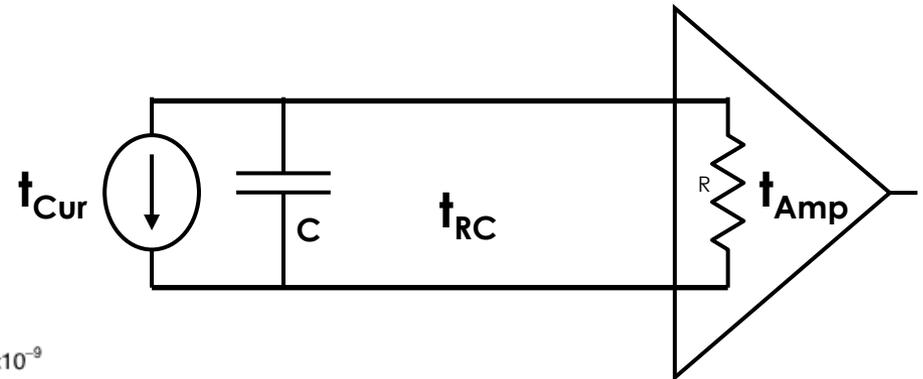
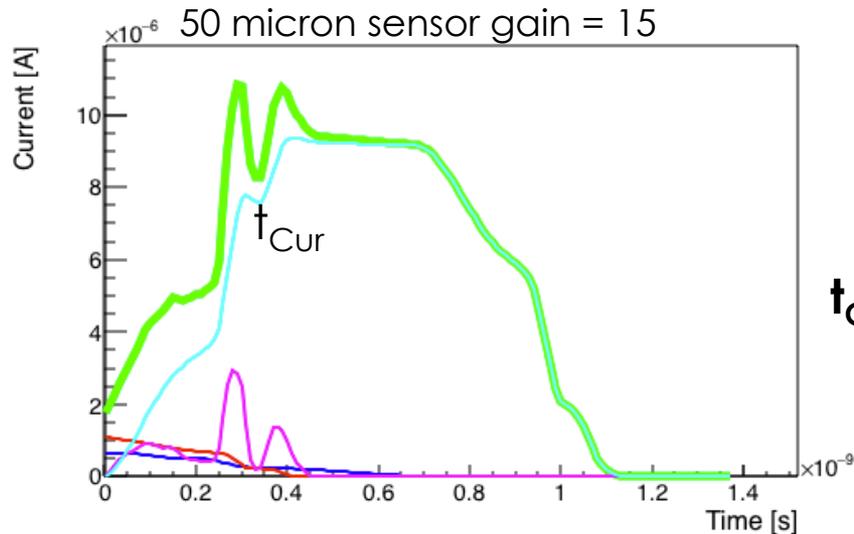
# The players: signal, noise and slope

Signal  $dV/dt$

Landau Noise

Shot Noise

Electronic Noise



The current rise time ( $t_{Cur}$ )

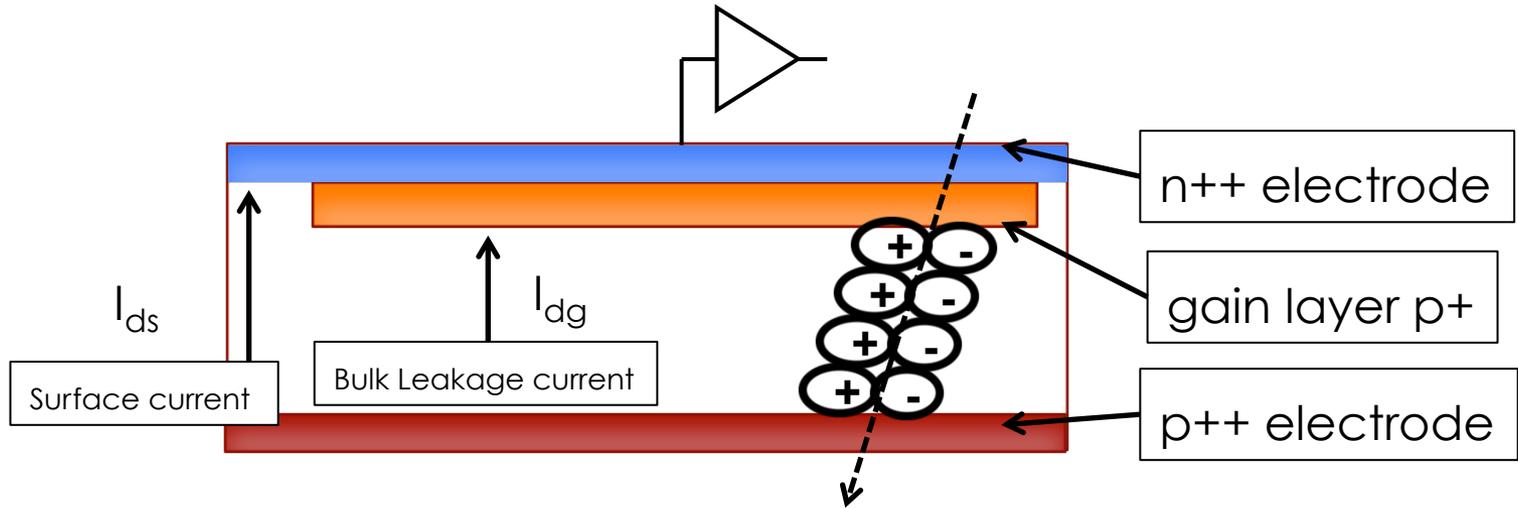
The RC circuit ( $t_{RC}$ )

Amplifier rise time ( $t_{Amp}$ )

There are 3 quantities determining the output rise time after the amplifier:

1. The signal rise time ( $t_{Cur}$ )
2. The RC circuit formed by the detector capacitance and the amplifier input impedance ( $t_{RC}$ )
3. The amplifier rise time ( $t_{Amp}$ )

# Shot noise in LGAD - APD



$$i_{Shot}^2 = 2eI_{Det} = 2e \left[ I_{Surface} + (I_{Bulk}) M^2 F \right]$$

Current density, nA/sqrt(f)

$$F = Mk + \left( 2 - \frac{1}{M} \right) (1 - k)$$

$$F \sim M^x$$

$k = e/h$  ionization rate

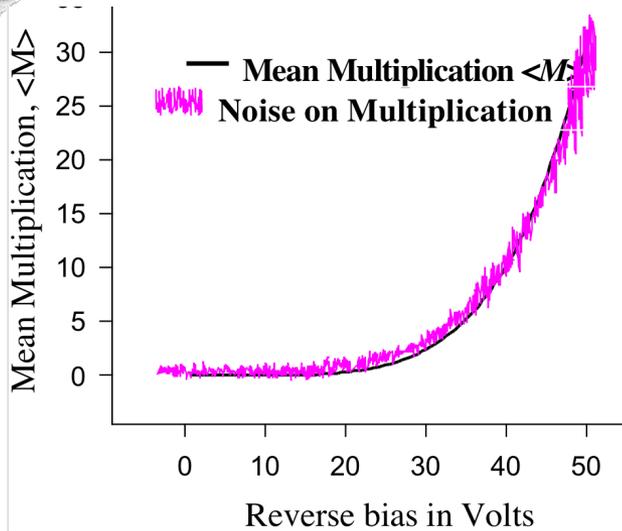
$x =$  excess noise index

$M =$  gain

Correction factor to the standard Shot noise, due to the noise of the multiplication mechanism

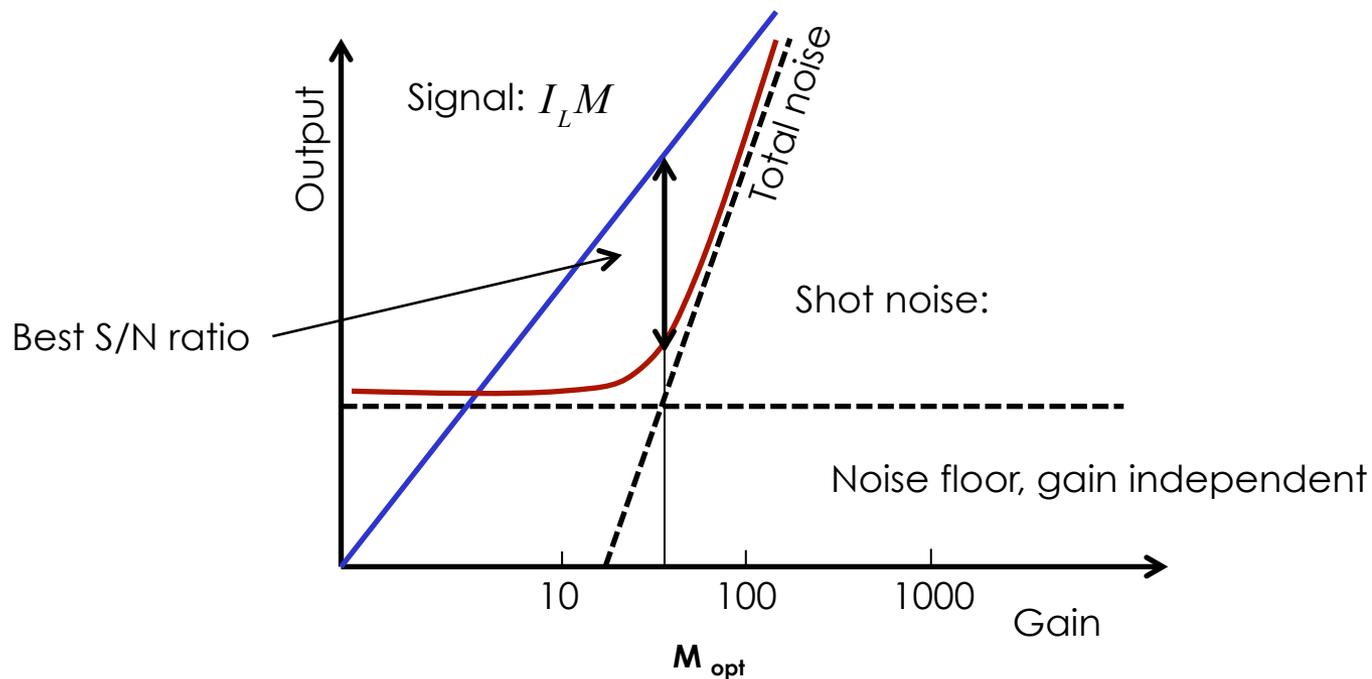
$$F = \frac{\langle M^2 \rangle}{\langle M \rangle^2} \Rightarrow \langle M^2 \rangle = \langle M \rangle^2 F$$

# Noise in LGAD & APD – Aide Memoire



**Noise increases faster than then signal → the ratio S/N becomes worse at higher gain.**

**There is an Optimum Gain value: 10-20?**



# Shot noise

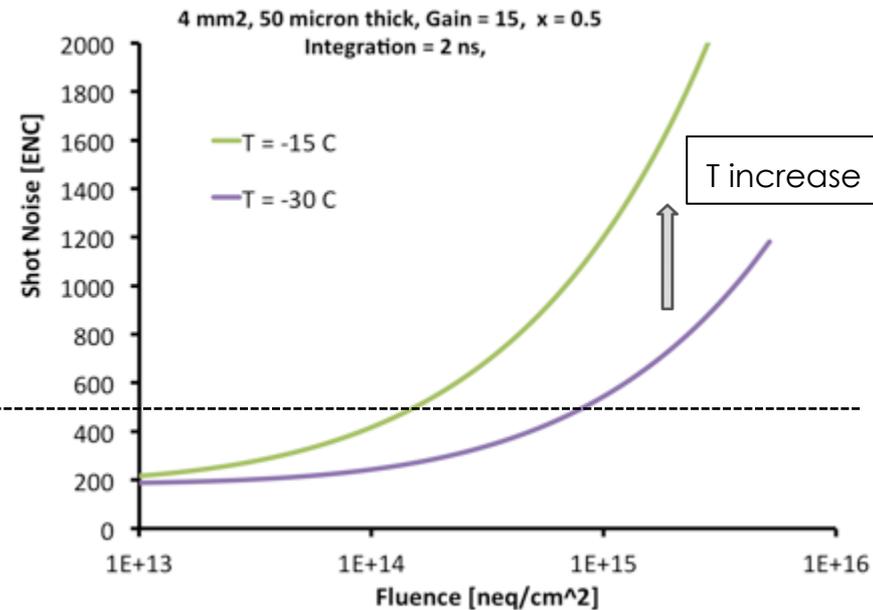
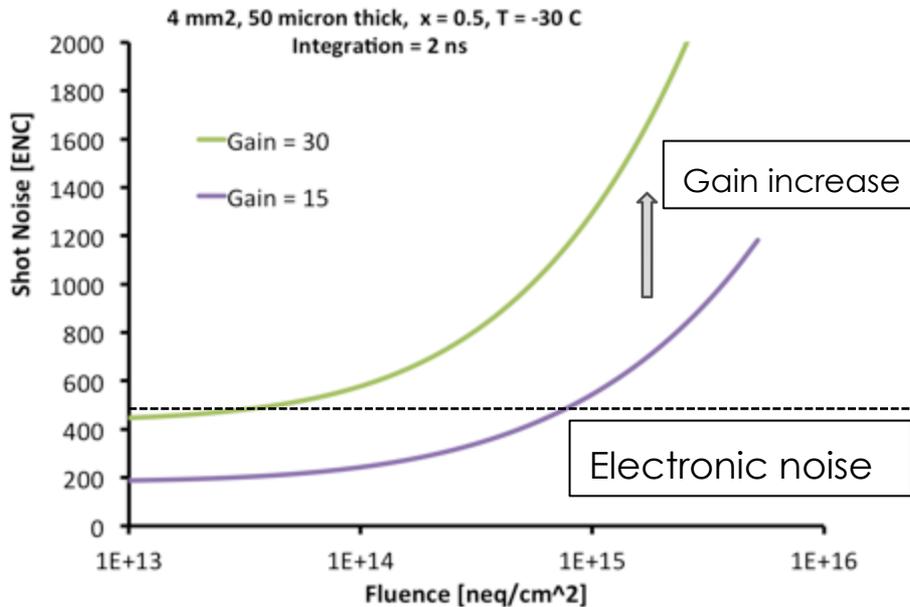
Let's assume a 4 mm<sup>2</sup> pad, 50 micron thick, and a electronic noise of 500 ENC

**What is the effect of shot noise as a function of radiation?**

Steep dependence on gain

$$I = \alpha * \Phi * \text{Volume} \quad \alpha = 3 \cdot 10^{-17} / \text{cm}$$

$$\text{Shot noise: } ENC = \sqrt{\int i_{\text{Shot}}^2 df} = \sqrt{\frac{I * (\text{Gain})^{2+x}}{2e}} * \tau_{\text{Int}}$$

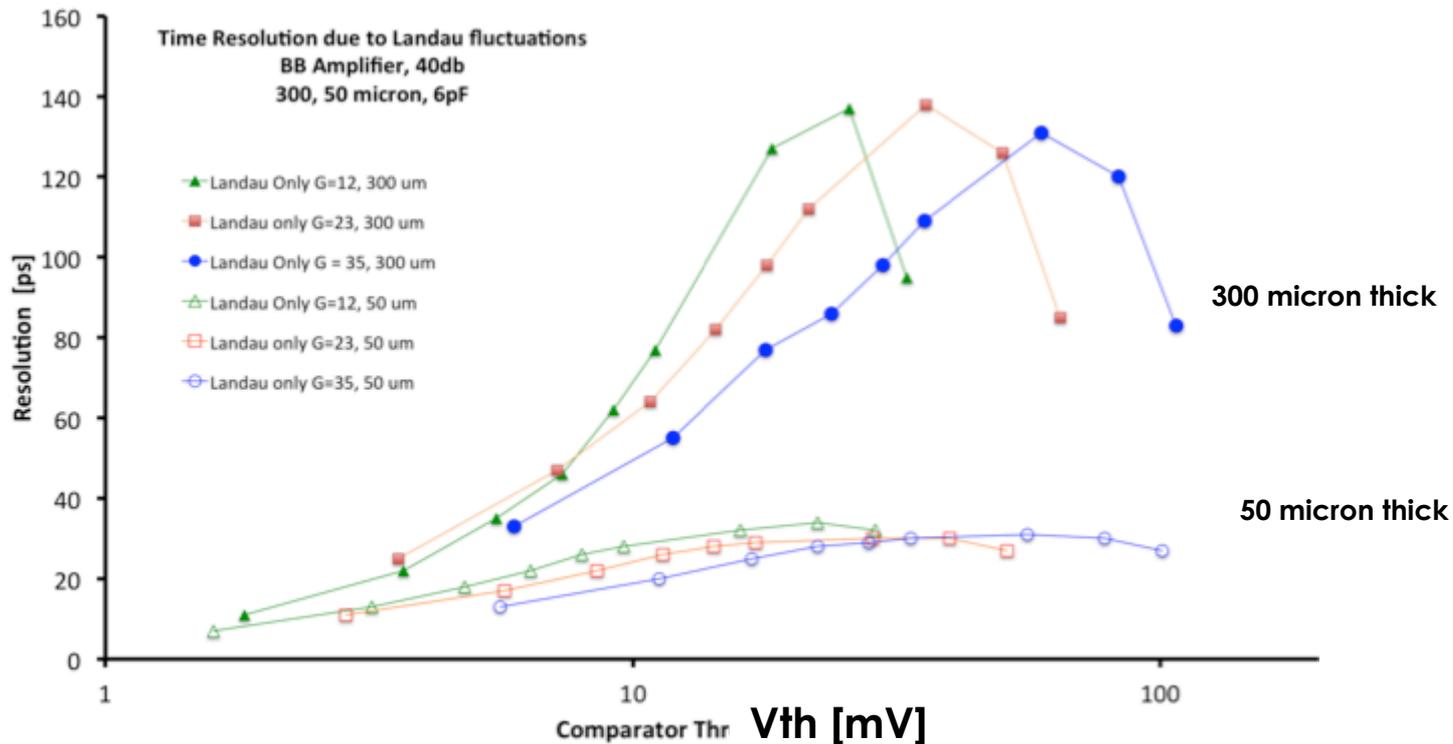


**To minimize Shot noise:**

- ➔ Low gain!! Keep the gain below ~ 20
- ➔ Cool the detectors
- ➔ Use small pads to have less leakage current

# Landau noise

Resolution due only to shape variation, assuming perfect time walk compensation



**To minimize Landau noise:**

- ➔ Set the comparator threshold as low as you can
- ➔ Use thin sensors

## Irradiation causes 3 main effects:

1. Decrease of charge collection efficiency due to trapping
2. Changes in doping concentration
3. Increased leakage current

### 1) Decrease of charge collection efficiency due to trapping

We ran a full simulation of CCE effect.

In 50 micron thick sensors the effect is

rather small: **up to  $10^{15}$  neq/cm<sup>2</sup> the**

**effect is negligible in the fast initial**

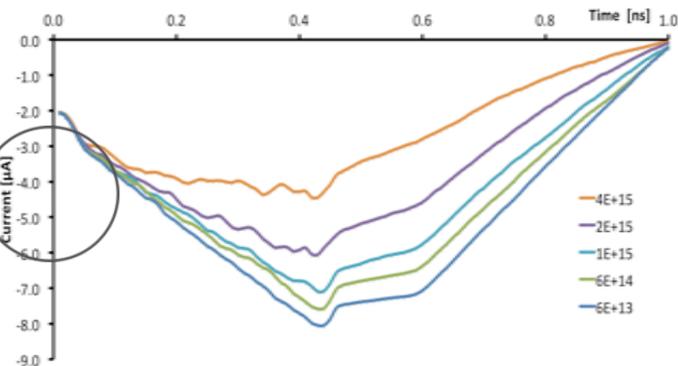
**edge used for timing.**

(poster Sec. A, B. Baldassarri)

Electronics need to be calibrated for

different signal shapes

Signal produced by a MIP in an n in p Si pad irradiated at different fluences  
(50µm, Vdepl(at fluence = 0) = 40V, Vbias = 800V, T = 300K)



## 2) Changes in doping concentration

There is evidence **that in thick sensors** dynamic effects cause an apparent “initial acceptor removal” at fluences above a few  $10^{14} n_{eq}/cm^2$

→ the “real” p-doping of the LGAD gain layer is deactivated.

### R&D paths:

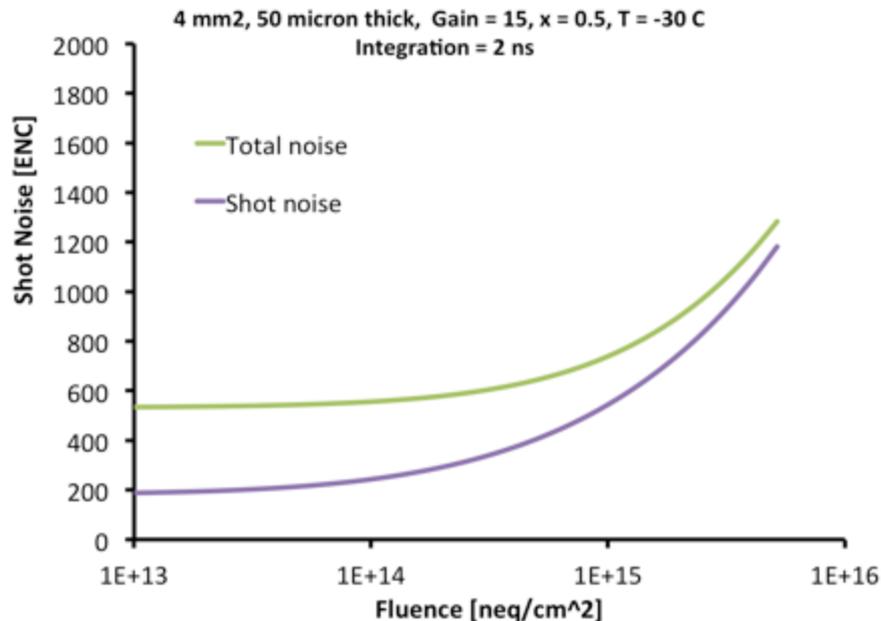
- Use Vbias to compensate for the loss on gain
- Use thin sensors: weaker dynamic effects
- Long term: Gallium doping

## 3) Increased leakage current

Assuming Gain  $\sim 15$ ,  $T = -30C$ ,

Shot noise starts to be important at fluences above  $\sim 10^{15} n_{eq}/cm^2$

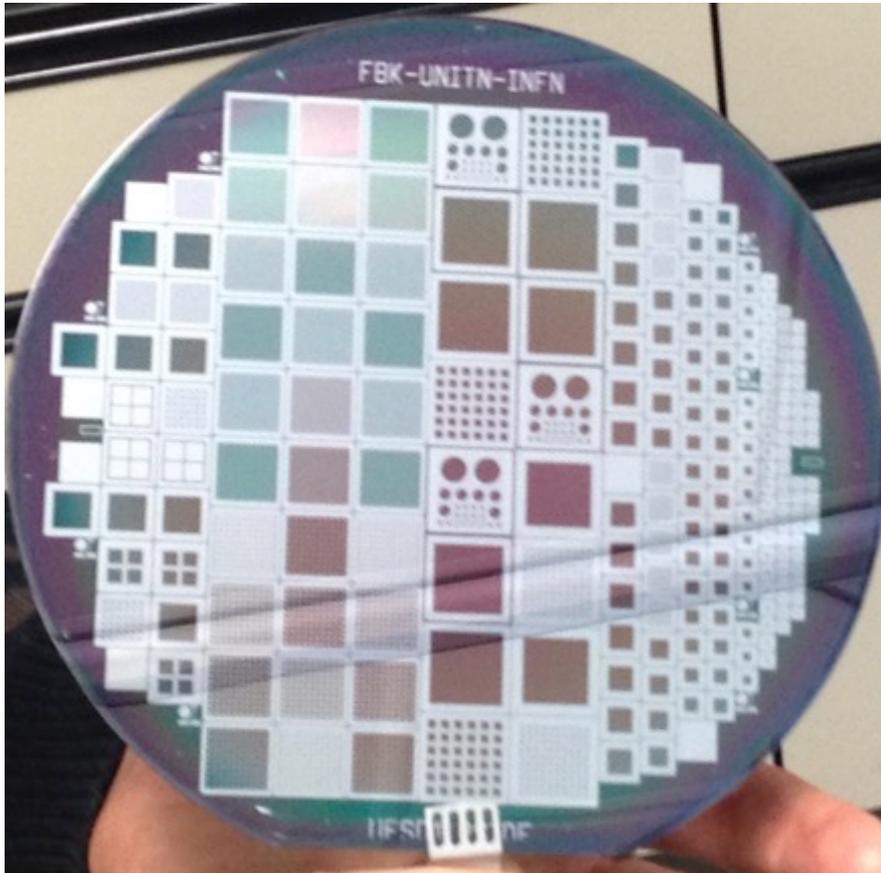
- Keep the sensor cold
- Low gain
- Small sensor



# Sensors: FBK & CNM

FBK 300-micron production  
Very successful, good gain and overall behavior

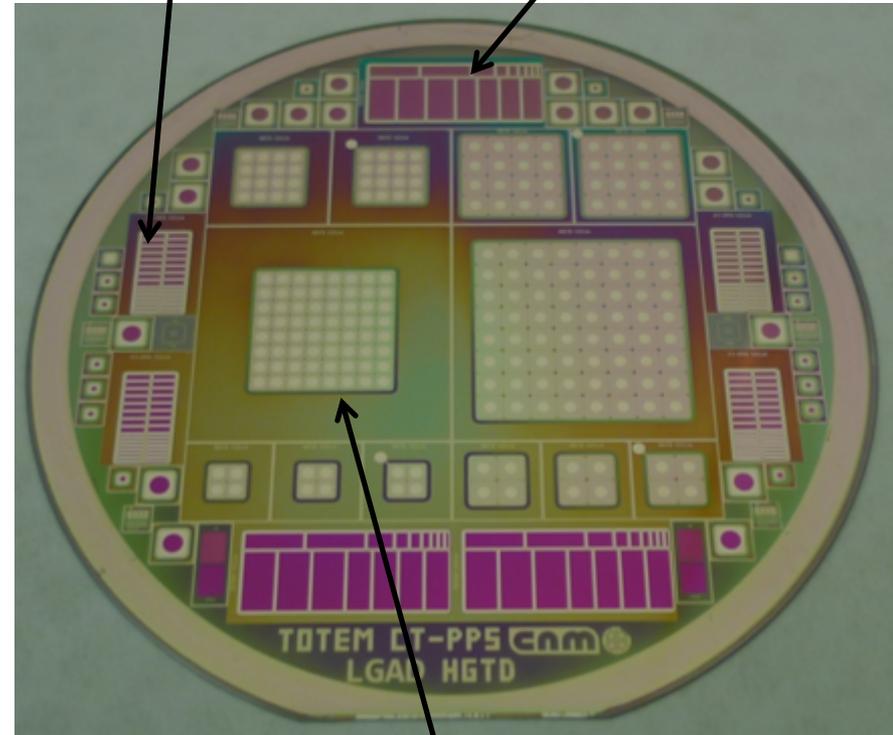
➔ We have now a second producer



CNM 75-micron  
CNM 50-micron production

x4 CT-PPS

x3 TOTEM



ATLAS High Granularity Timing Det.

# Sensors for the CMS CT-PPS detectors

New production of 50 micron thick, segmented UFSD sensors.

Gain  $\sim 15$

32 fat strip array for CT-PPS

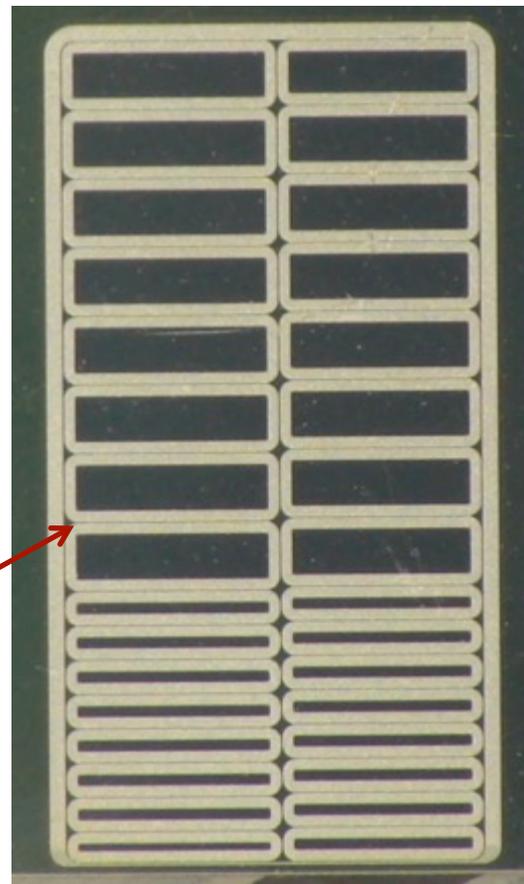
Strips:

3 mm x 0.5 mm

3 mm x 1 mm

Distance between pads: 50 micron

→ Able to produce segmented UFSD

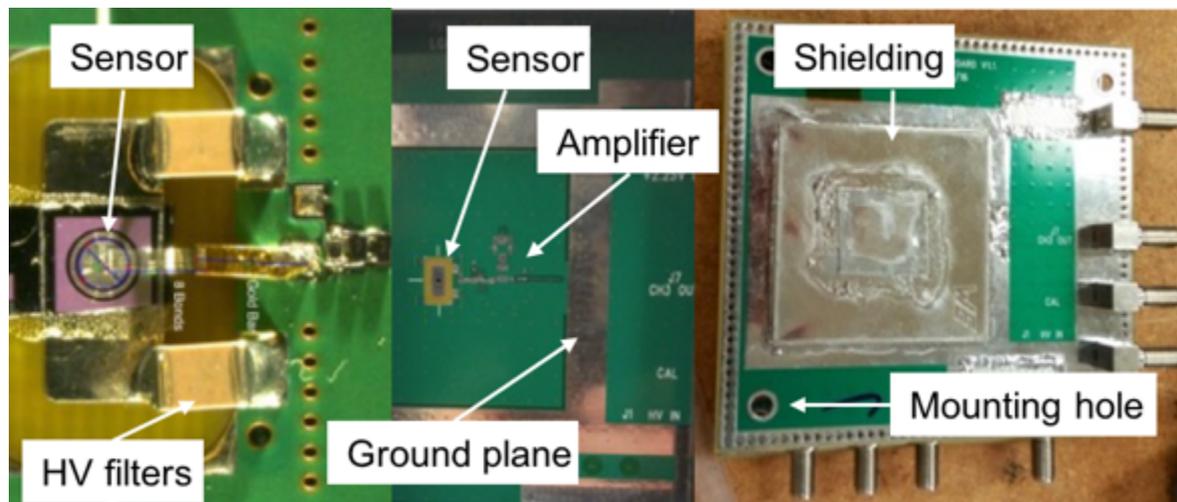


12 mm

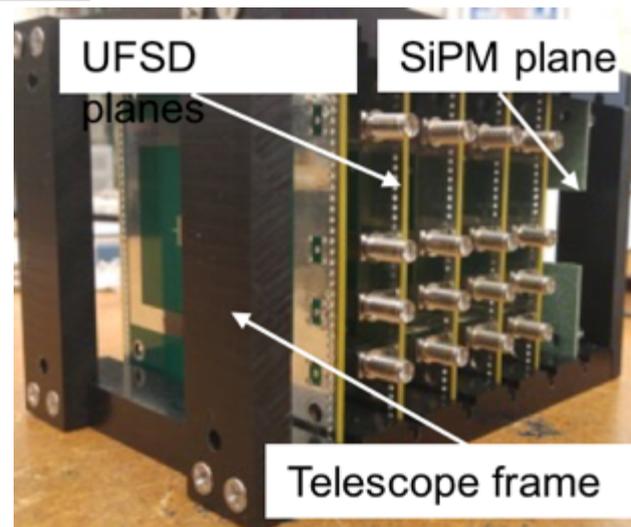
6 mm

# Latest results on UFSD time resolution

Fully custom made UFSD read-out (UCSC)



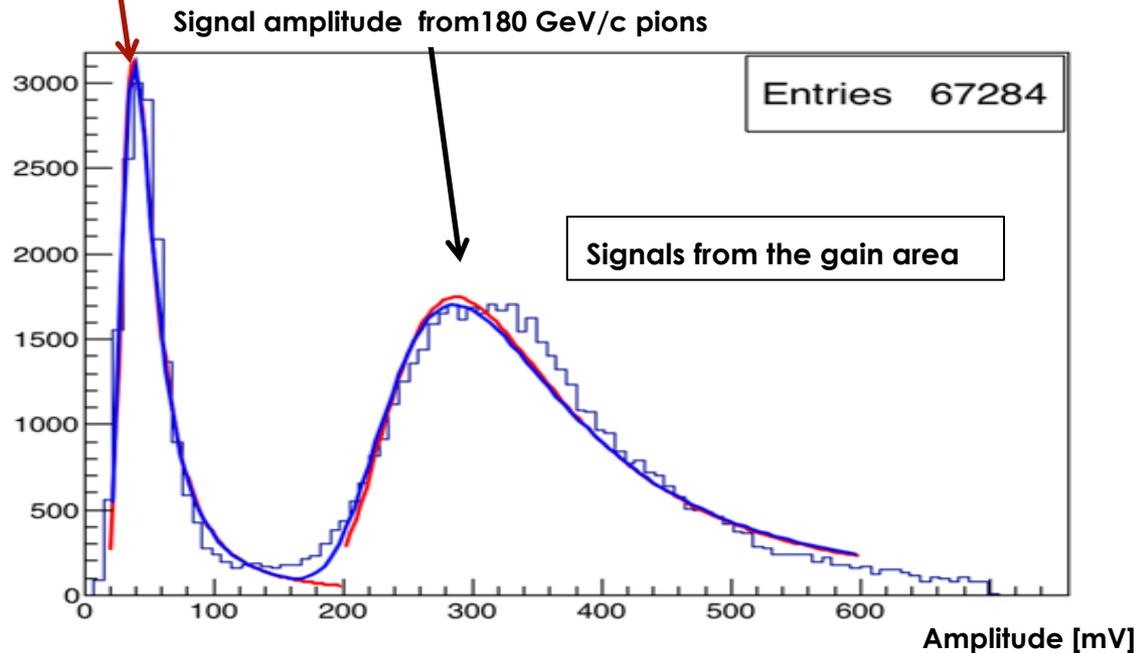
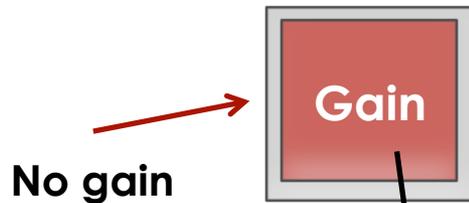
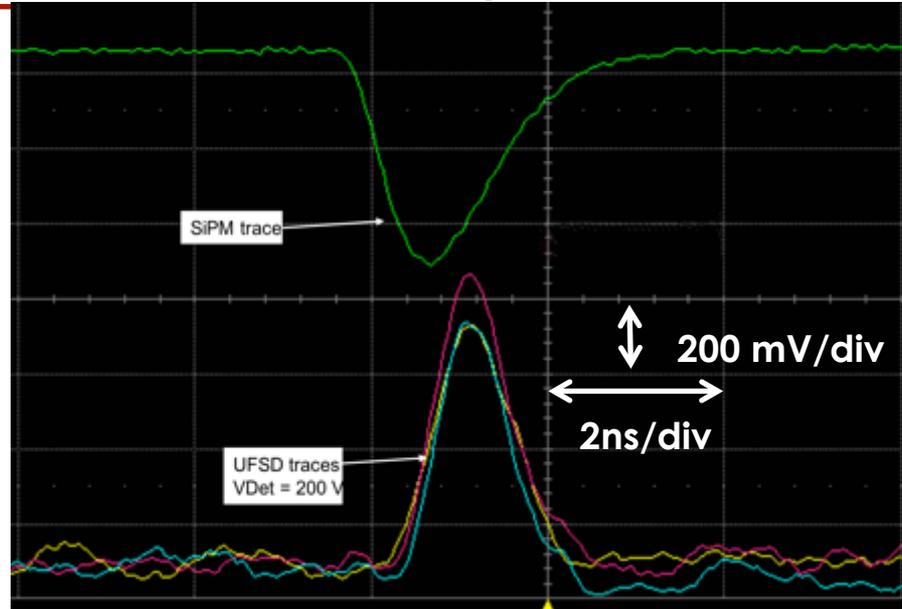
**CNM production of thin sensors  
(50 micron)**



# An example of the signals

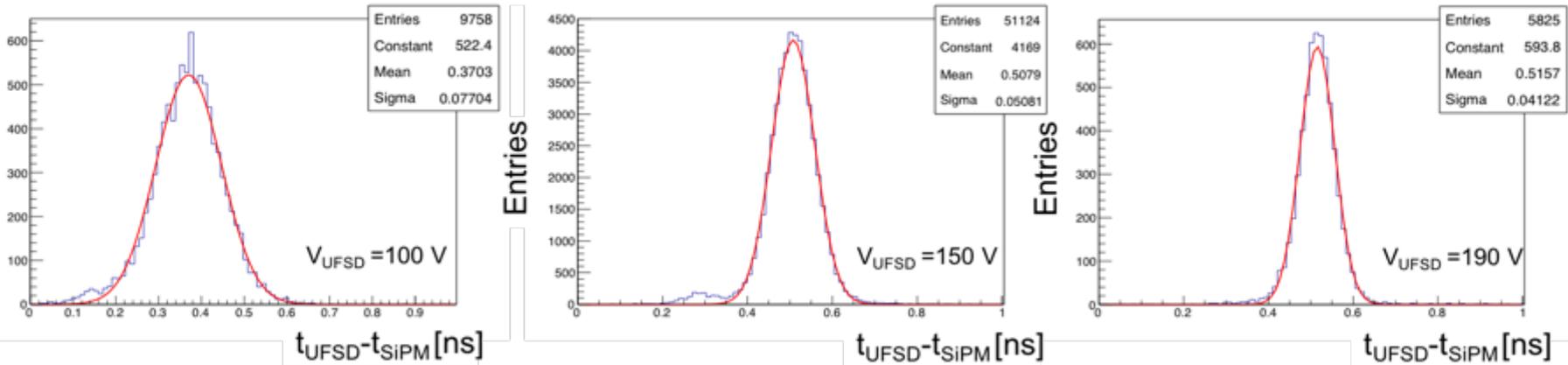
Fast, low noise signals, ideal for timing

The sensor has a “no gain” frame, ideal for gain calibration with MIPS



# Time resolution as difference UCSC-SiPM

We used a very accurate (~ 15 ps) SiPM as trigger

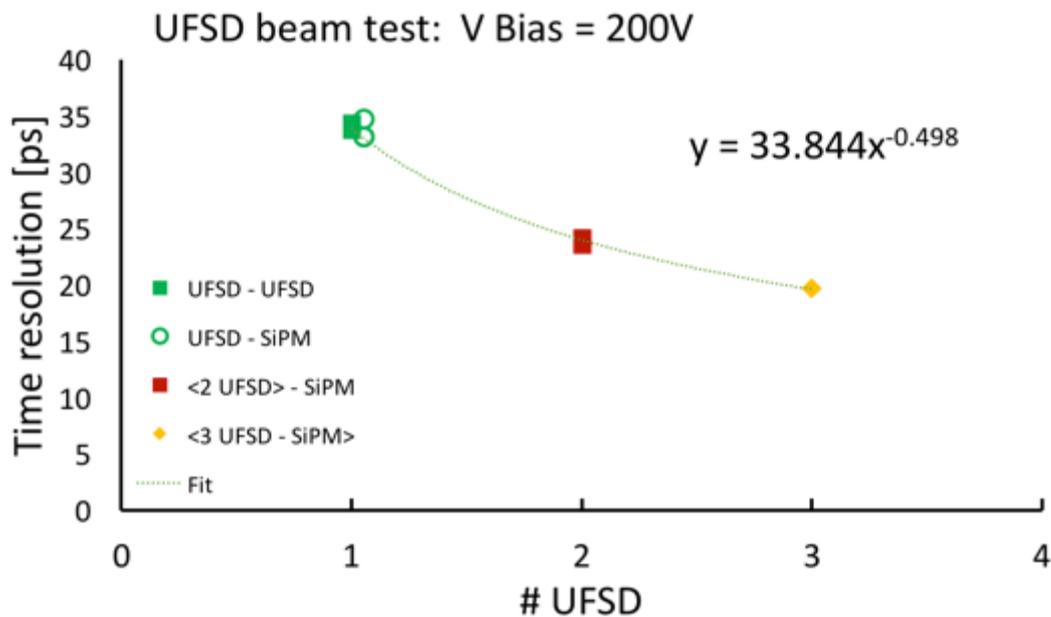


## Multiple UFSD tracking system

Timing Resolution [ps]		
Vbias [V]	200V	240V
N=1 :	34.6	25.6
N=2 :	23.9	18.0
N=3 :	19.7	14.8

Submitted to NIMA

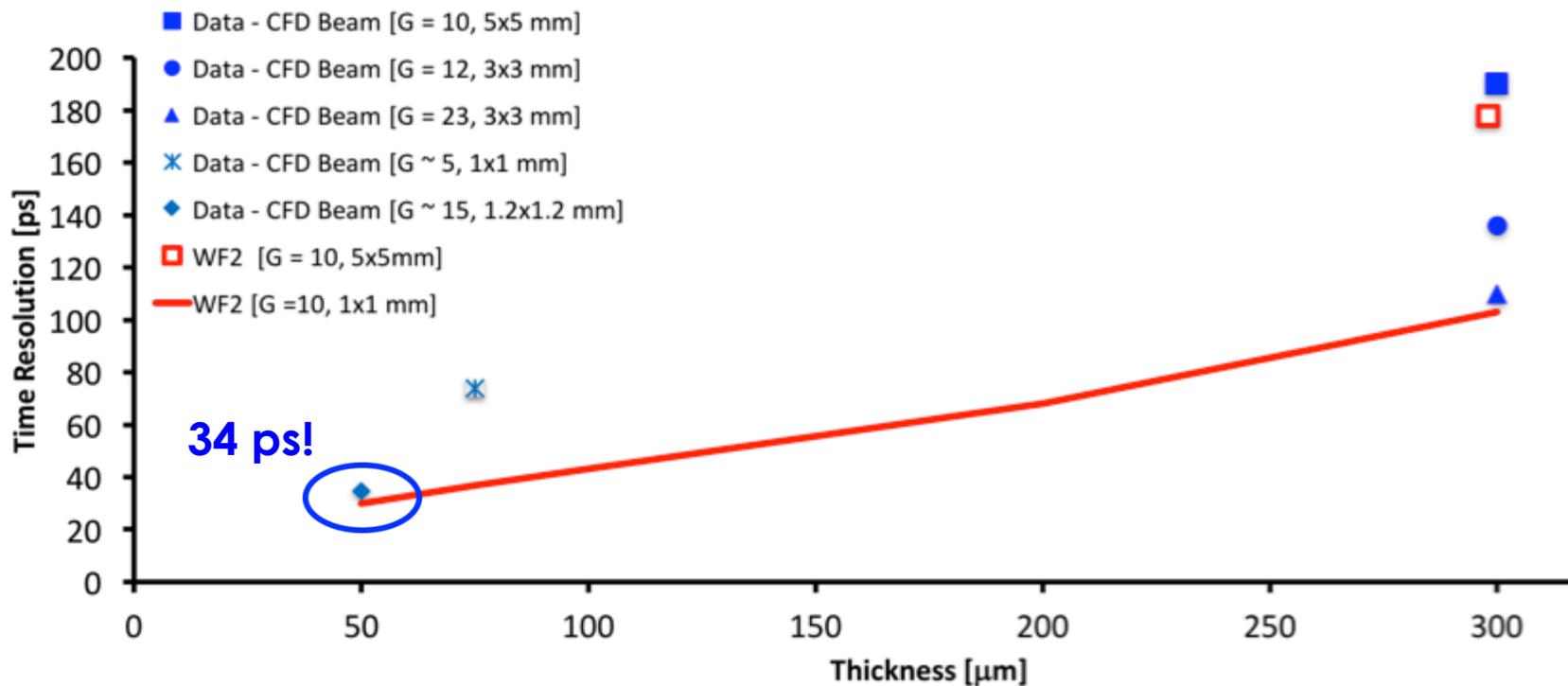
<http://arxiv.org/abs/1608.08681v1>



# Summary of UFSD beam test results

- 2014 Frascati: UFSD  $7 \times 7 \text{ mm}^2$   $300 \mu\text{m}$  ( $C = 12 \text{ pF}$ , Gain = 10)
- 2014 CERN: UFSD  $7 \times 7 \text{ mm}^2$   $300 \mu\text{m}$  ( $C = 12 \text{ pF}$ , Gain = 10)
- 2015 CERN: UFSD  $3 \times 3 \text{ mm}^2$   $300 \mu\text{m}$  ( $C = 4 \text{ pF}$ , Gain = 10 - 20)
- 2015 CERN: UFSD  $1 \times 1 \text{ mm}^2$   $75 \mu\text{m}$  ( $C = 2 \text{ pF}$ , Gain = 5)
- 2016 CERN: UFSD  $1.2 \times 1.2 \text{ mm}^2$   $50 \mu\text{m}$  ( $C = 3 \text{ pF}$ , Gain = 15)

CNM - LGAD



# Summary and outlook

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## Tracking in 4 Dimensions is a very powerful tool

Low gain Avalanche Detectors have the potential to bring this technique to full fruition using gain  $\sim 10$  and thin sensors

Why **low** gain?

Milder electric fields, possible electrodes segmentation, lower shot noise, no dark count, behavior similar to standard Silicon detectors

Why **thin** sensors?

Higher signal steepness, more radiation resistance, easier to achieve parallel plate geometry, smaller Landau Noise

Next steps:

- Radiation hard studies
- Electronics for larger sensors (20-30 pF)

# Acknowledgments

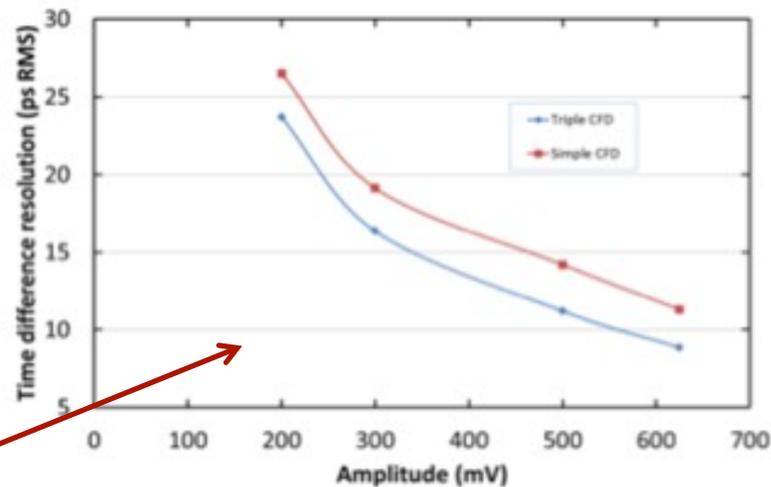
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- INFN – Gruppo V
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- U.S. Department of Energy grant number DE-SC0010107
- The RD50 collaboration

# The APD approach

The key to this approach is the large signal: if your signal is large enough, everything becomes easy.



So far they reported excellent time resolution on a single channel.

To be done:

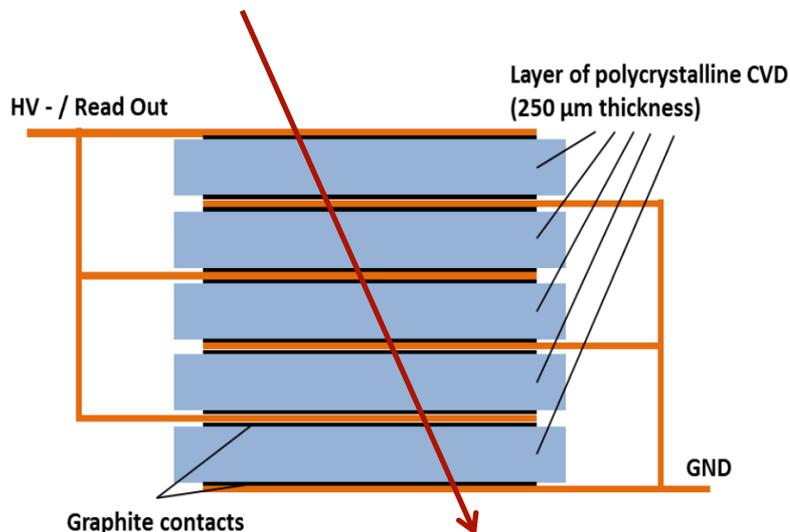
- Radiation hardness above  $10^{14} n_{eq}/cm^2$
- Fine Segmentation
- How to deal with shot noise (proportional to gain)

# The Diamond approach

Diamond detectors have small signal: two ways of fighting this problem

## 1) Multilayer stack

The signal is increased by the sum of many layers while keeping the rise time short



**Best resolution:**  
**~ 100 ps**

## 2) Grazing

The particle crosses the diamond sensor along the longitudinal direction



# Gain in Silicon detectors

Gain in silicon detectors is commonly achieved in several types of sensors. It's based on the avalanche mechanism that starts in high electric fields:  **$E \sim 300 \text{ kV/cm}$**

Charge multiplication

Gain:

- $\alpha$  = strong E dependance
- $\alpha \sim 0.7 \text{ pair}/\mu\text{m}$  for electrons,
- $\alpha \sim 0.1$  for holes

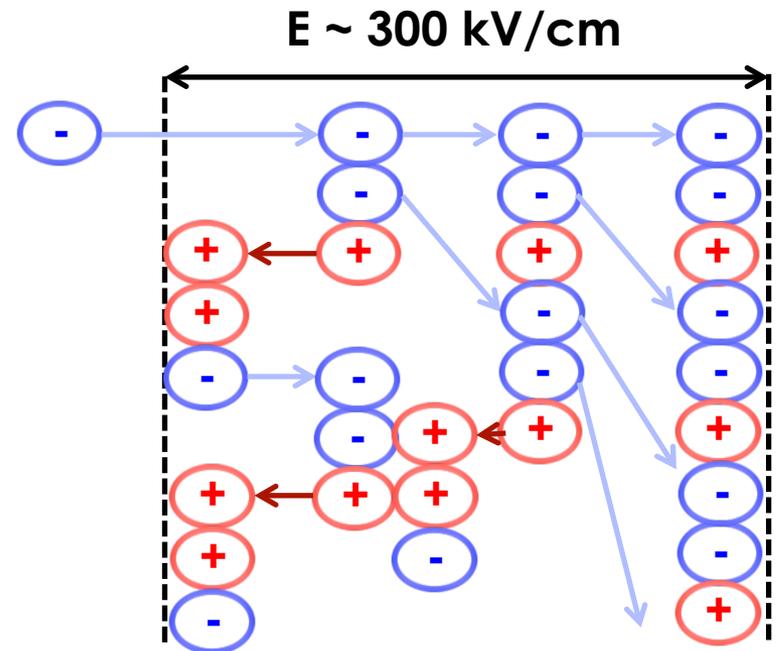
$$N(l) = N_0 \cdot e^{\alpha \cdot l}$$

$$G = e^{\alpha \cdot l} \quad \alpha_{e,h}(E) = \alpha_{e,h}(\infty) \cdot \exp\left(-\frac{b_{e,h}}{|E|}\right)$$

Concurrent multiplication of electrons and holes generate very high gain

**Silicon devices with gain:**

- **APD: gain 50-500**
- **SiPM: gain  $\sim 10^4$**



# TOFFEE chip

Fully custom made chip for UFSD read-out

8 input channels

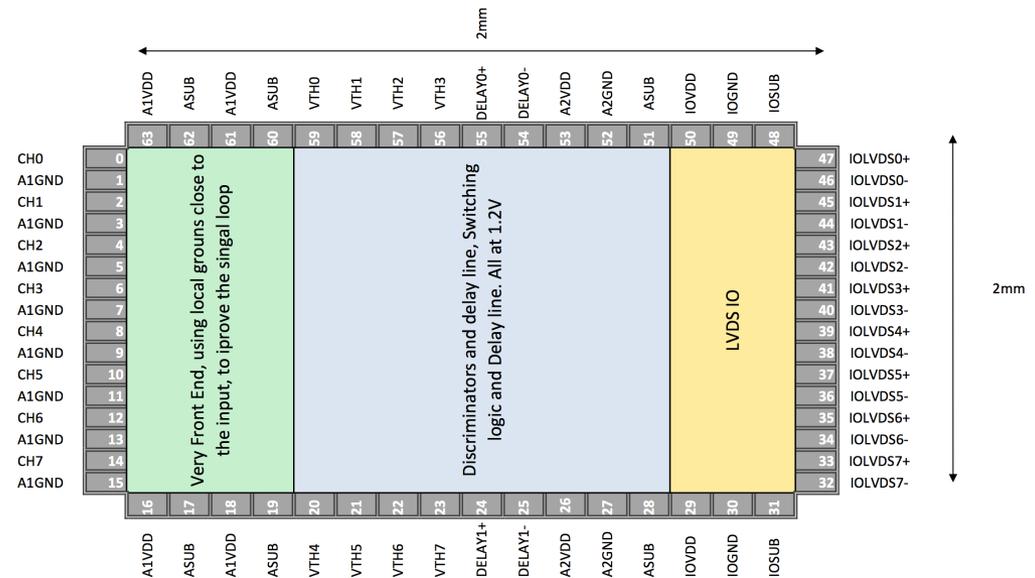
8 LVDS output suited for HPTDC

Available mid summer

Time resolution:

~ 50 ps with 6 fC

~ 30 ps with 10 fC



# What is the signal of one e/h pair?

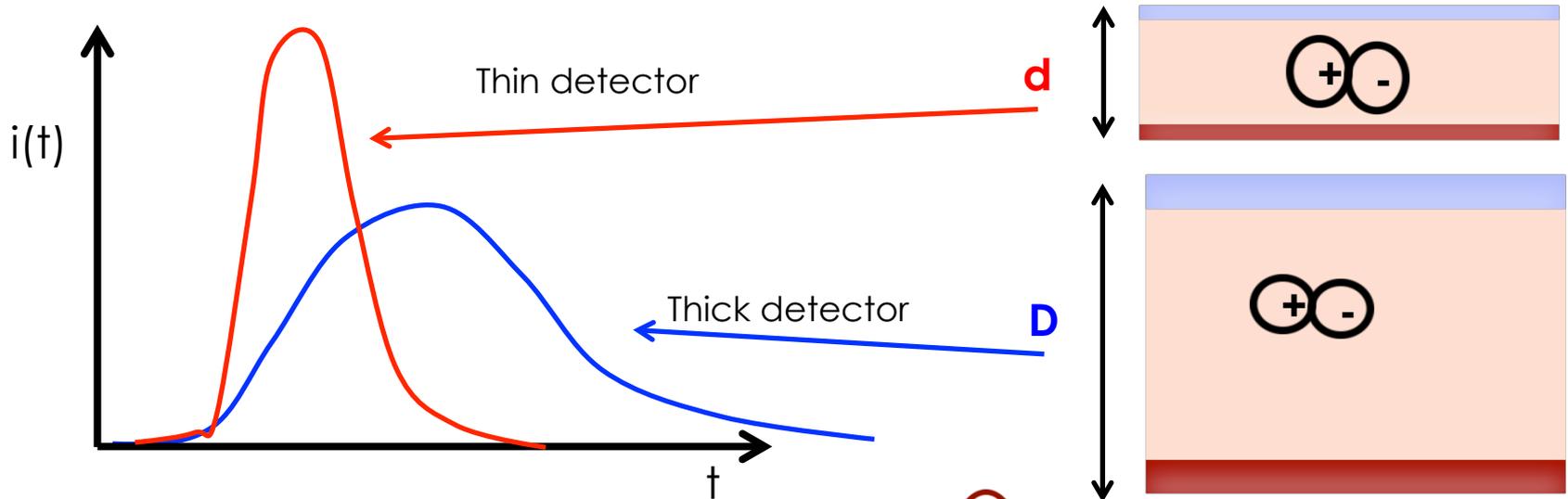
(Simplified model for pad detectors)

Let's consider **one single electron-hole pair**.

The integral of their currents is equal to the electric charge,  $q$ :

$$\int [i_{el}(t) + i_h(t)] dt = q$$

However **the shape of the signal depends on the thickness  $d$** :  
thinner detectors have higher slew rate



→ **One e/h pair generates higher current in thin detectors**

$$i \propto qv \left( \frac{1}{d} \right)$$

← Weighting field

# Possible approaches for timing systems

We need to minimize this expression:

$$\sigma_t^2 = \left( \frac{N}{dV/dt} \right)^2$$

- **APD** (silicon with gain  $\sim 100$ ): maximize  $dV/dt$ 
  - Very large signal
- **Diamond**: minimize  $N$ , minimize  $dt$ 
  - Large energy gap, very low noise, low capacitance
  - Very good mobility, short collection time  $t_r$
- **LGAD** (silicon with gain  $\sim 10$ ): minimize  $N$ , moderate  $dV/dt$ 
  - Low gain to avoid shot noise and excess noise factor